



HAIR Based Sensing and Actuation

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Biomimetic HAIR-Based Sensing and Actuation

- Our focus: new sensor/actuators to meet constraints (SWaP + cost + performance) for micro air vehicles for ARL's MAST program, where COTS are unsuitable
- **Example:** *Air flow sensor for wind gust state estimation for stable MAV control*
- MAST air flow sensor requirements
 - Low power, stand-alone, robust
 - Measure gusting air flow in range of 0.1 to 10+ meters/sec
 - Fast sensor response for dynamic flight control: > 30 Hz, ideally 100 Hz
 - Determine gust direction: minimum resolution is four in-plane quadrant directions

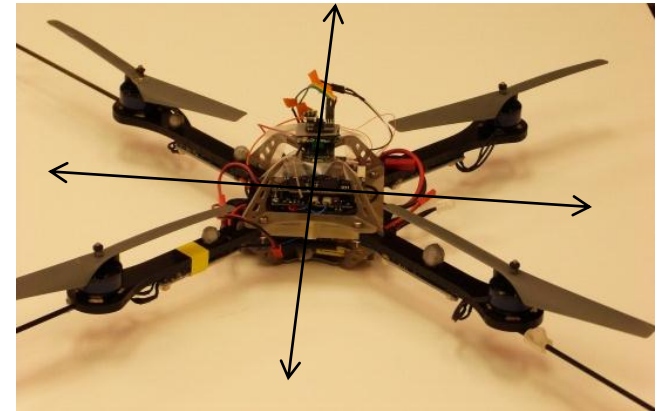
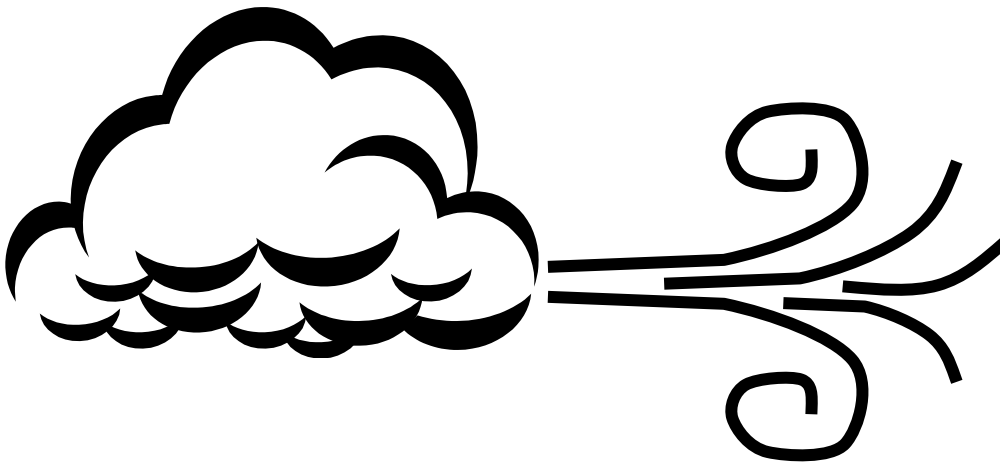
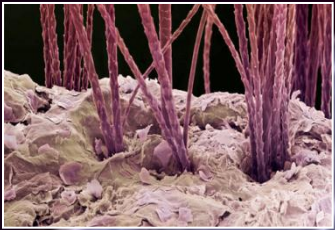


Image of U Maryland (J. Sean Humbert)
macro-quadrotor

Biomimetic Sensing

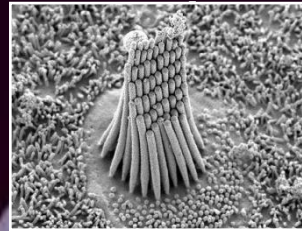
Many different types of sensors are used in biological systems. The one structure that is used most abundantly is the HAIR.

Gas/Chemical Sensing

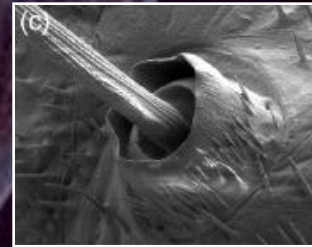


Filtering Particle Capture

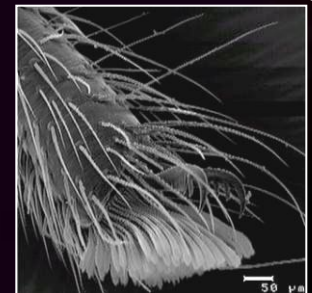
Cilia for Balance & Inertial



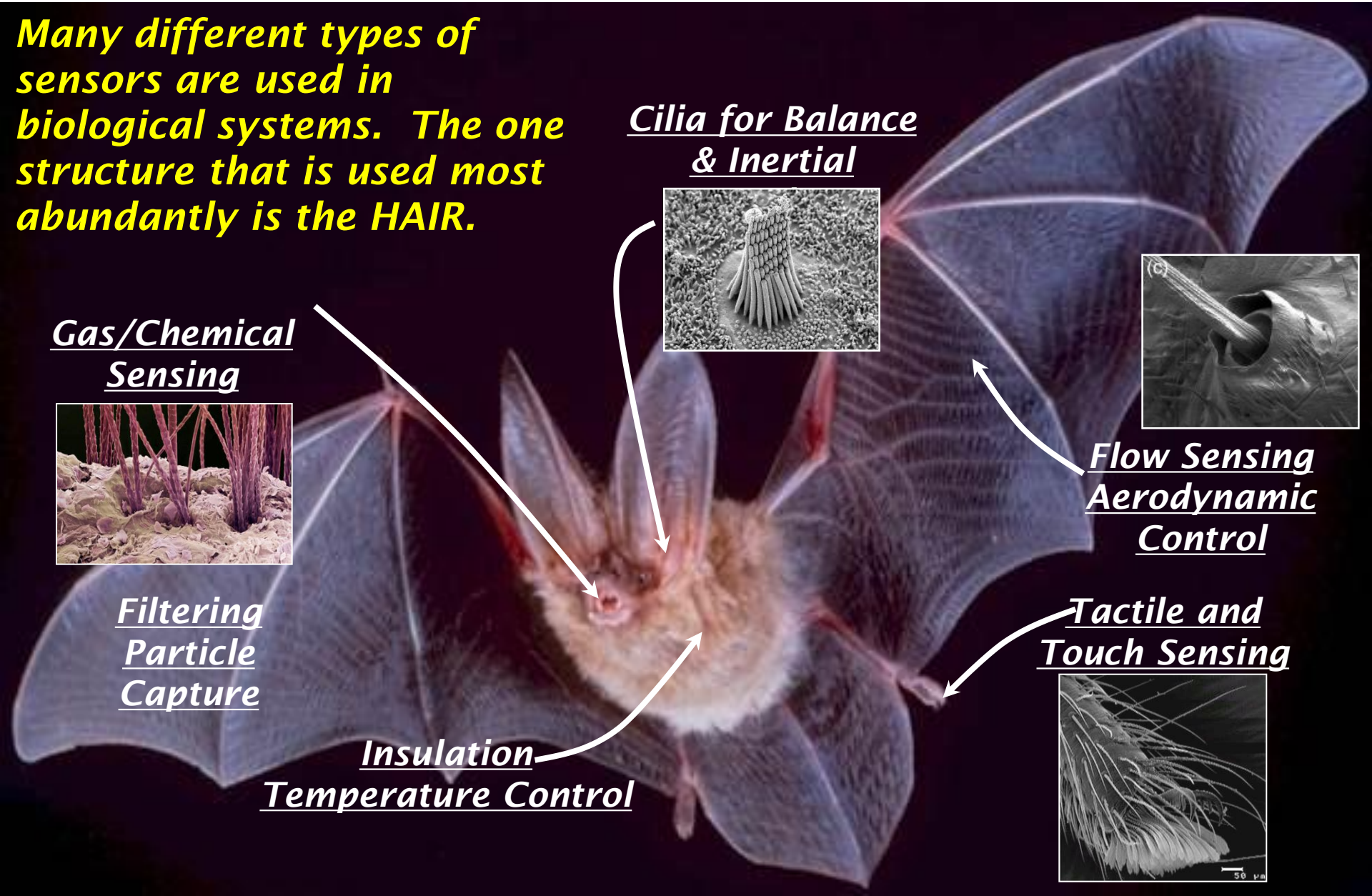
Flow Sensing Aerodynamic Control



Tactile and Touch Sensing



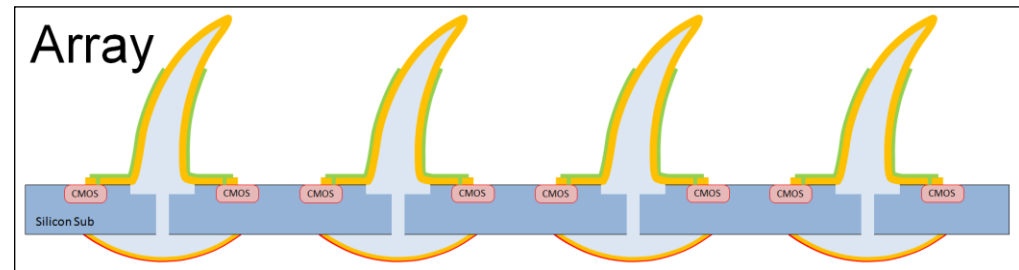
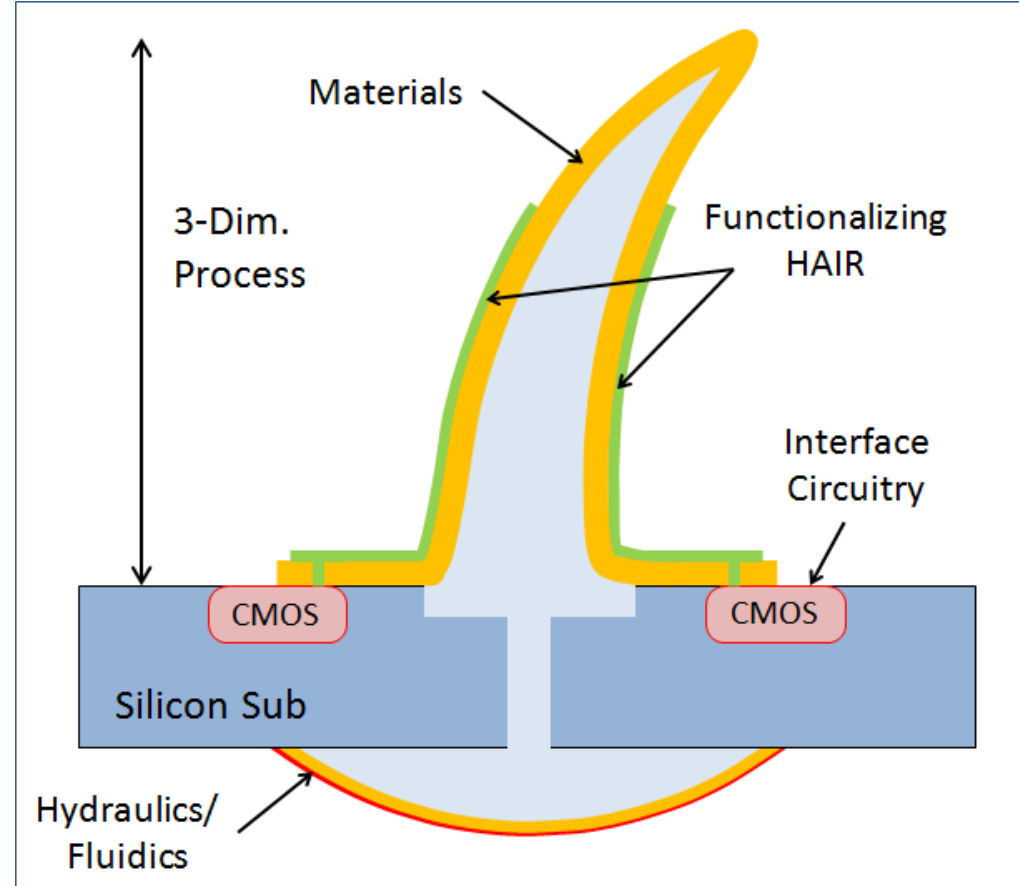
Insulation Temperature Control



High-performance, Actuation and Integrated sensing Research (HAIR)

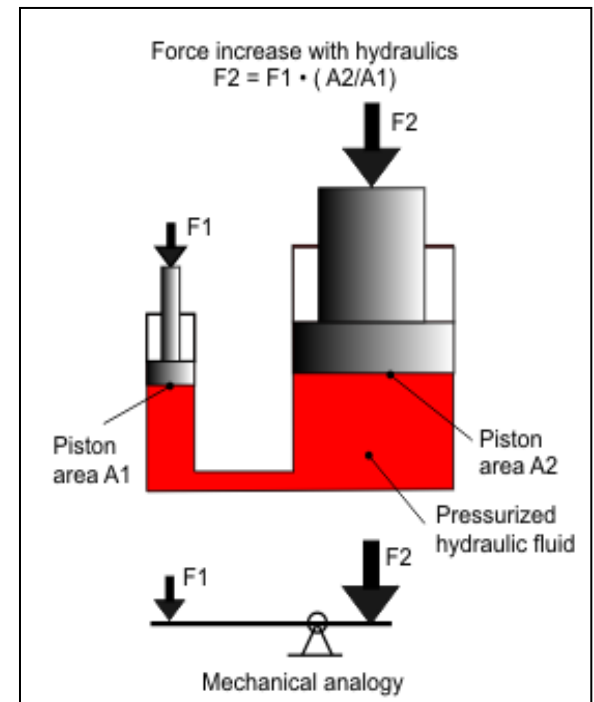
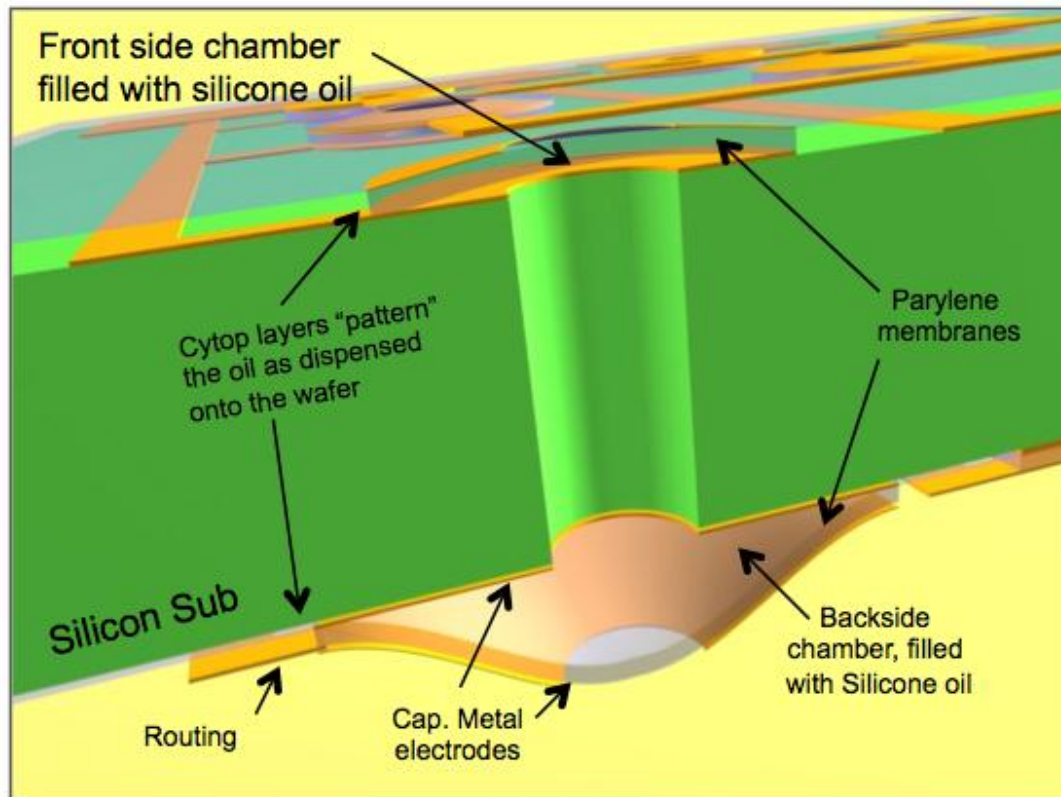
Key biomimetic components

1. Material
2. 3-D Process
3. Hydraulics / fluidics
4. Functionalization
5. Circuit Integration
6. Array



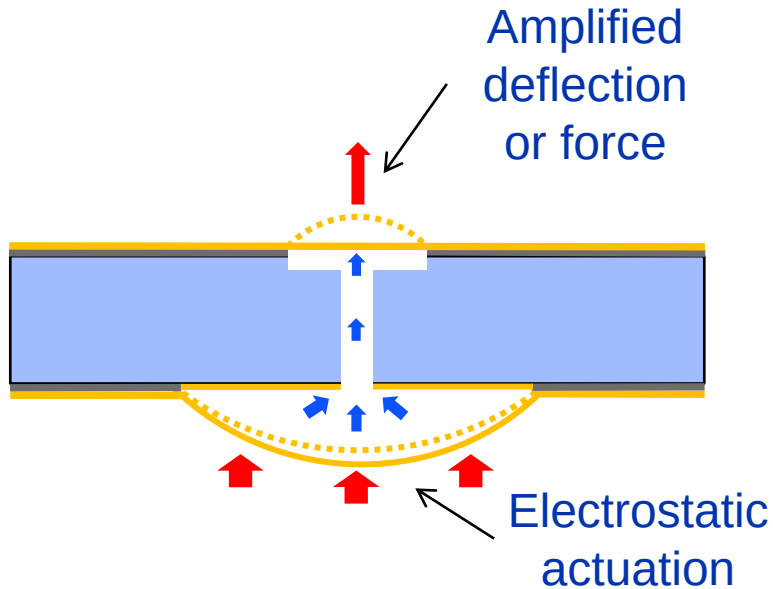
Electrostatic Micro-hydraulics

- Key concept: combine electrostatics & micro-hydraulics for large-force, large-deflection, low-power actuation and low-power, high-dynamic range sensing
- Structural features
 1. Two connected chambers on opposite sides of a wafer, capped with membranes
 2. Capacitive metal electrodes allow electrostatic actuation or sensing
 3. Encapsulated incompressible liquid dielectric constant > 1 (i.e., air) increases capacitance thus improving electrostatic coupling



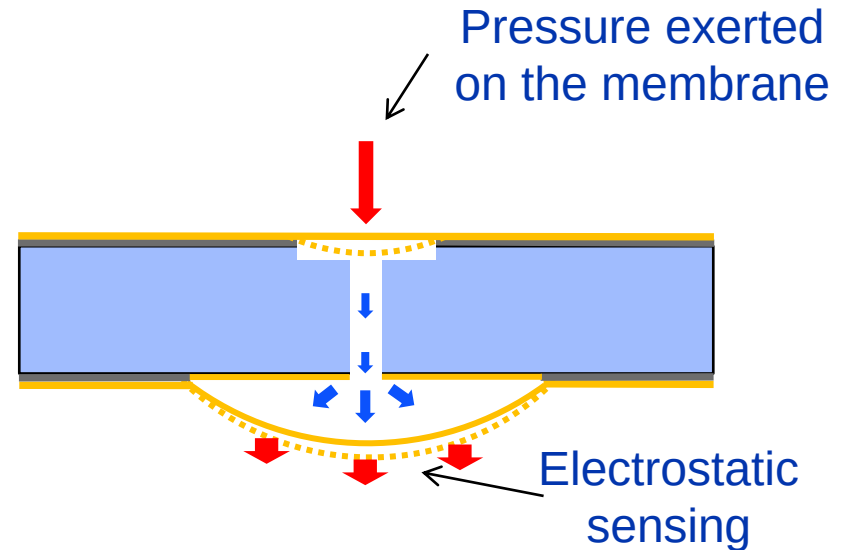
Sensing & Actuation through Micro-Hydraulics

Actuation Mode



- **Electrostatic actuation**
- Hydraulic amplification of force or deflection

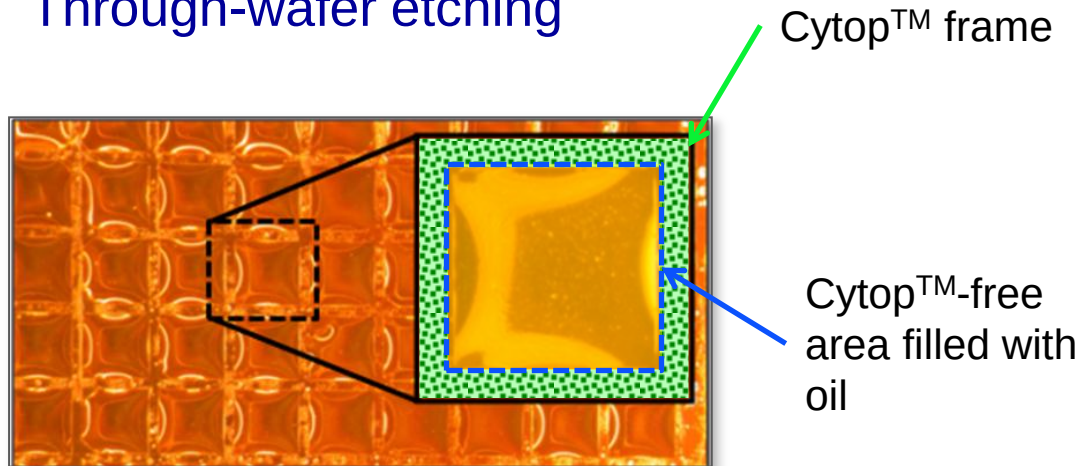
Sense Mode



- External pressure applied (via touch, air flow, etc.)
- Hydraulic amplification of force or deflection
- **Electrostatic Sensing**

Micro-Hydraulic Fabrication Process

1. Recess on both sides
 - Definition of capacitance gap
 - **Shape formation** of the liquid
2. Electrode on one/both side(s)
 - Actuation and/or sensing
3. Cytop™ layer and channel formation
 - Hydrophobic layer repels the silicone oil
 - Liquid will be contained in all the Cytop™-free areas
4. Through-wafer etching



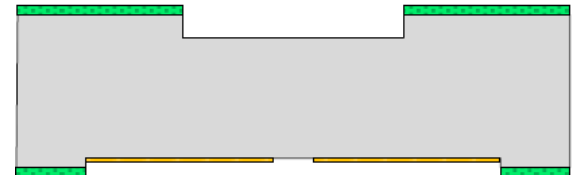
1) Trench etching



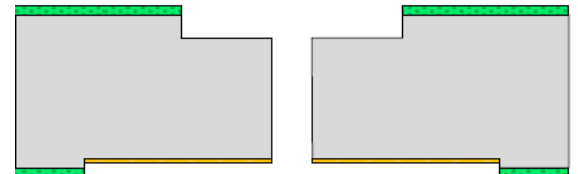
2) Cr/Au electrode



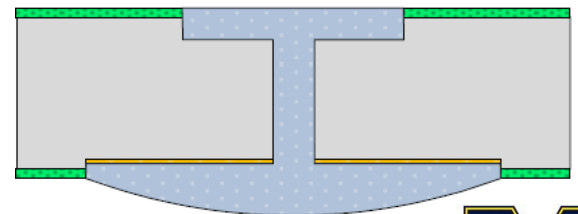
3) Cytop™ layer



4) Thru-wafer etching



5) liquid dispensing

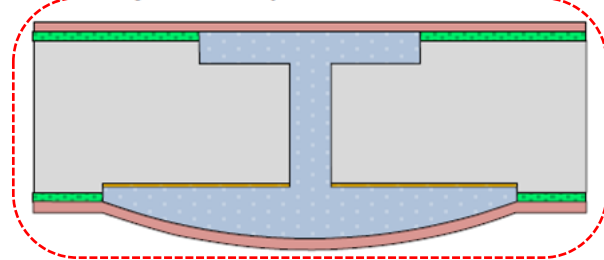


Sadeghi, Kim and Najafi, Digest MEMS 2010, pp. 15-18

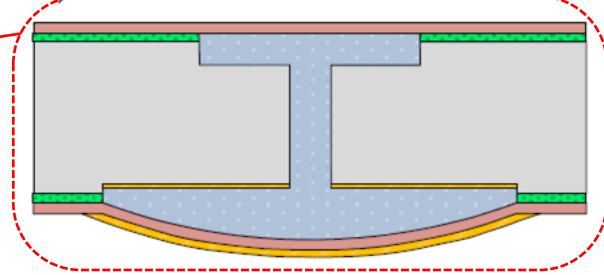
Micro-Hydraulic Fabrication Process

5. Liquid dispensing
 - Liquid weight and surface tension on the back side are at equilibrium
 - → **double-sided process**
6. Parylene coating
7. Second electrode deposition

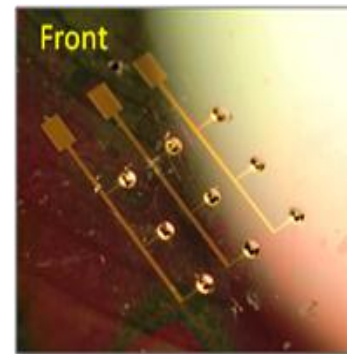
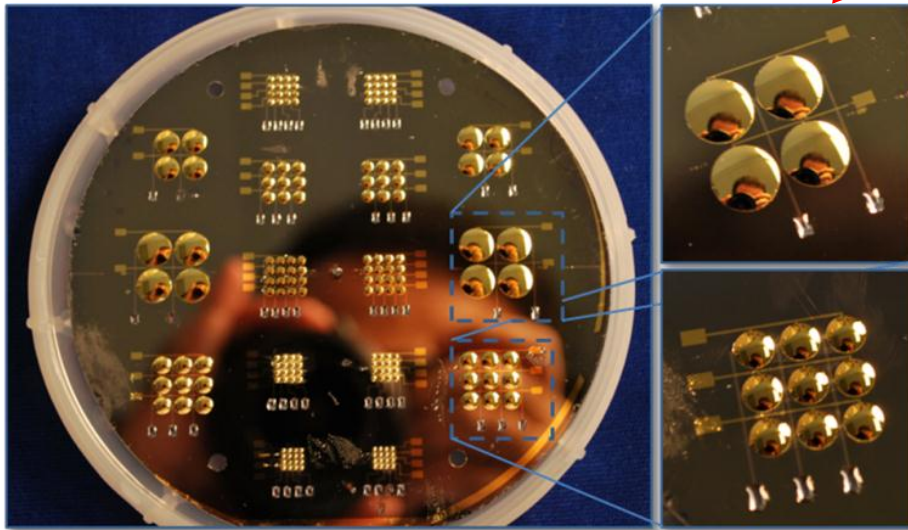
6) Parylene deposition



7) Cr/Au electrode

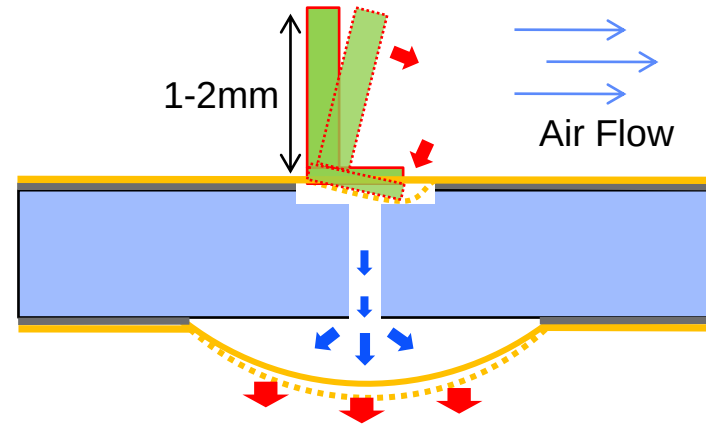
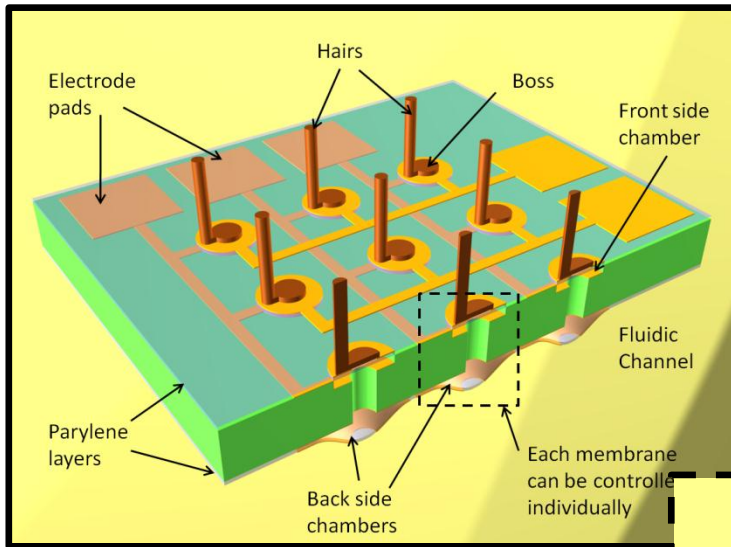


Wafer level process for bubble-free liquid encapsulation

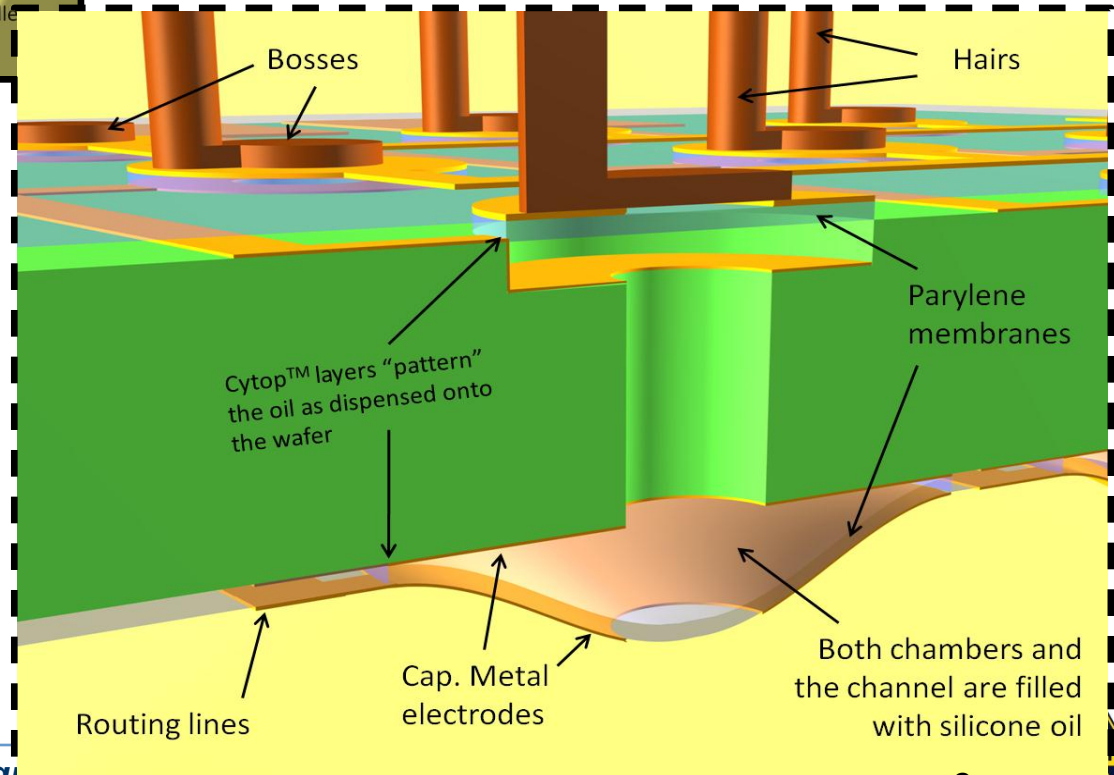


Sadeghi, Kim and Najafi, Digest MEMS 2010, pp. 15-18

Airflow Sensor using Micro-Hydraulics

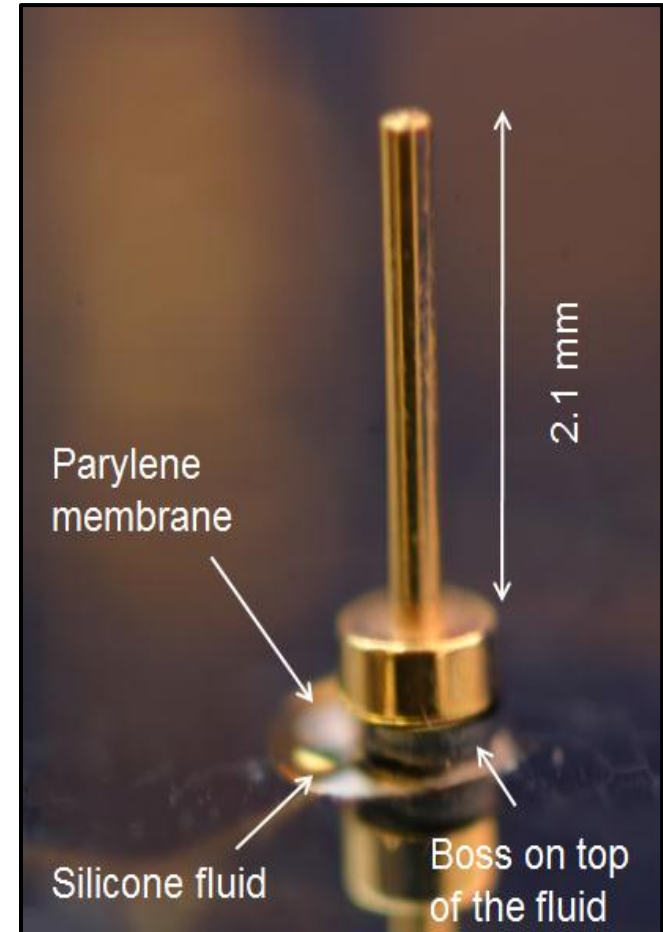
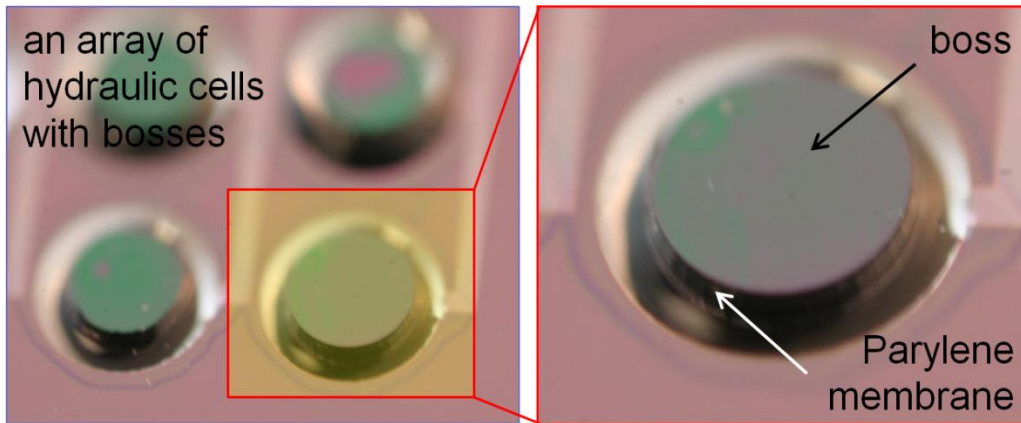
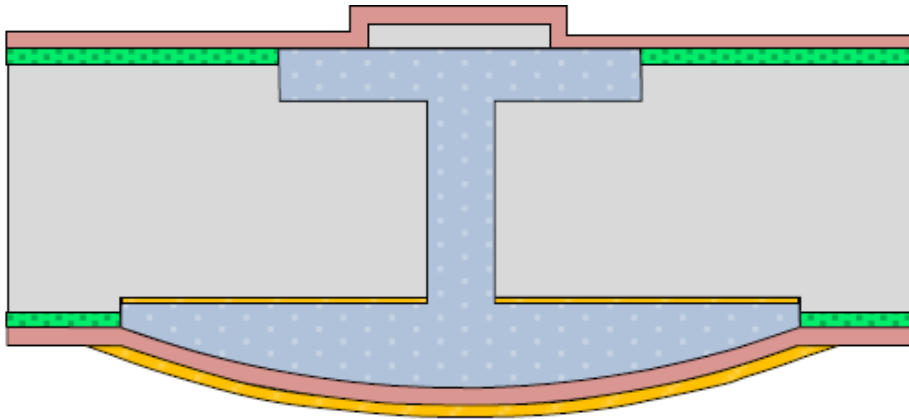


- **3-D boss + hair:**
converts fluid drag force into pressure
- **Micro-hydraulics:**
converts ΔP into capacitance change
- **Arrays:**
offer sensing of flow directionality



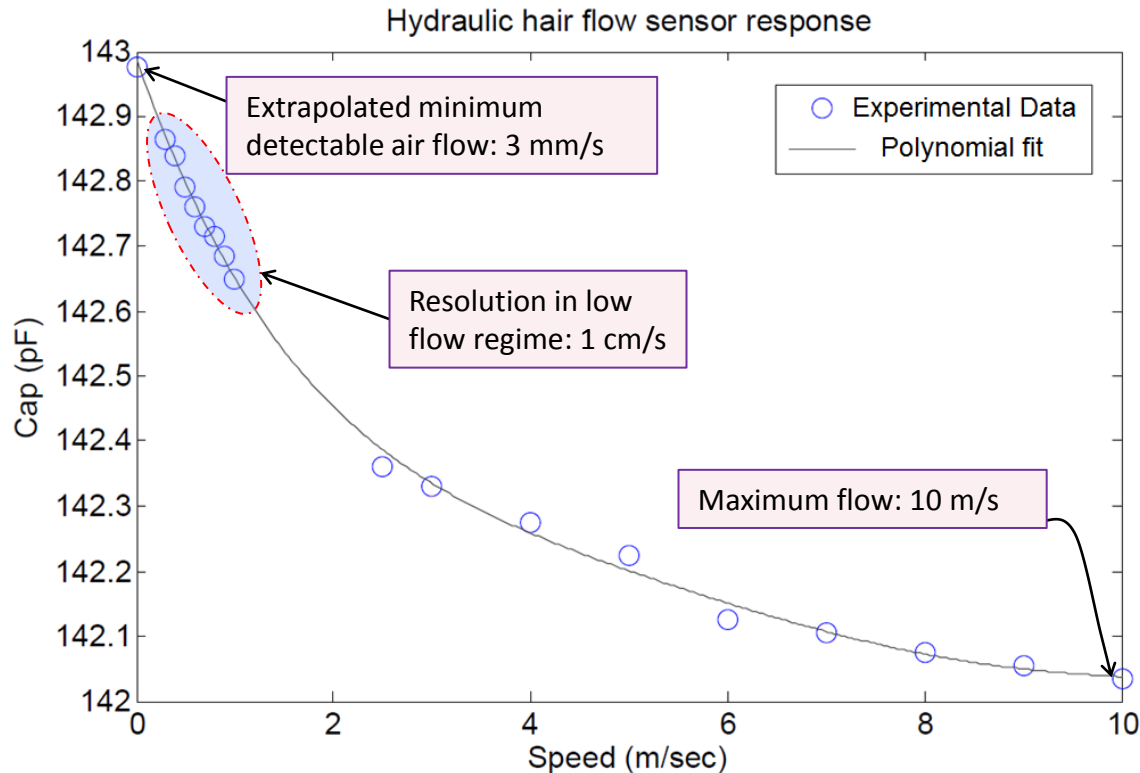
Integration of Boss

- Self-aligned silicon boss acts as platform for attaching hairs
 - Boss is placed after liquid dispensing
 - After Parylene encapsulation, cilia is attached over boss



1st Generation Device, Experimental Results

- Average sensitivity* = 333 fF/(m/s)
- Extrapolated minimum detectable air flow: **3 mm/s** assuming 1fF ΔC detection
- Full scale range : **10 m/s**
- **But slow time response**

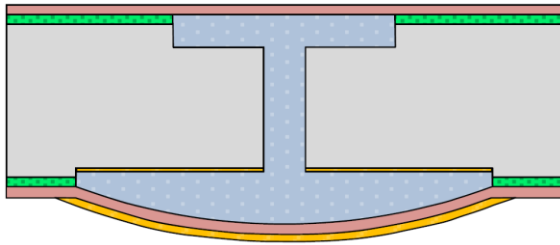


*Sadeghi,
Peterson and
Najafi, Digest
IEDM 2011, pp.
29.4.1-4*

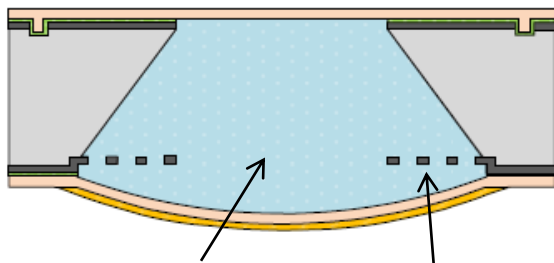
* Tests on multiple samples of the same size yielded sensitivities of 230 to 440 fF/ms⁻¹, with an average of 333 fF/ms⁻¹ over 10 m/s range (based on 5 samples)

Reducing sensor response time

Straight wall channel



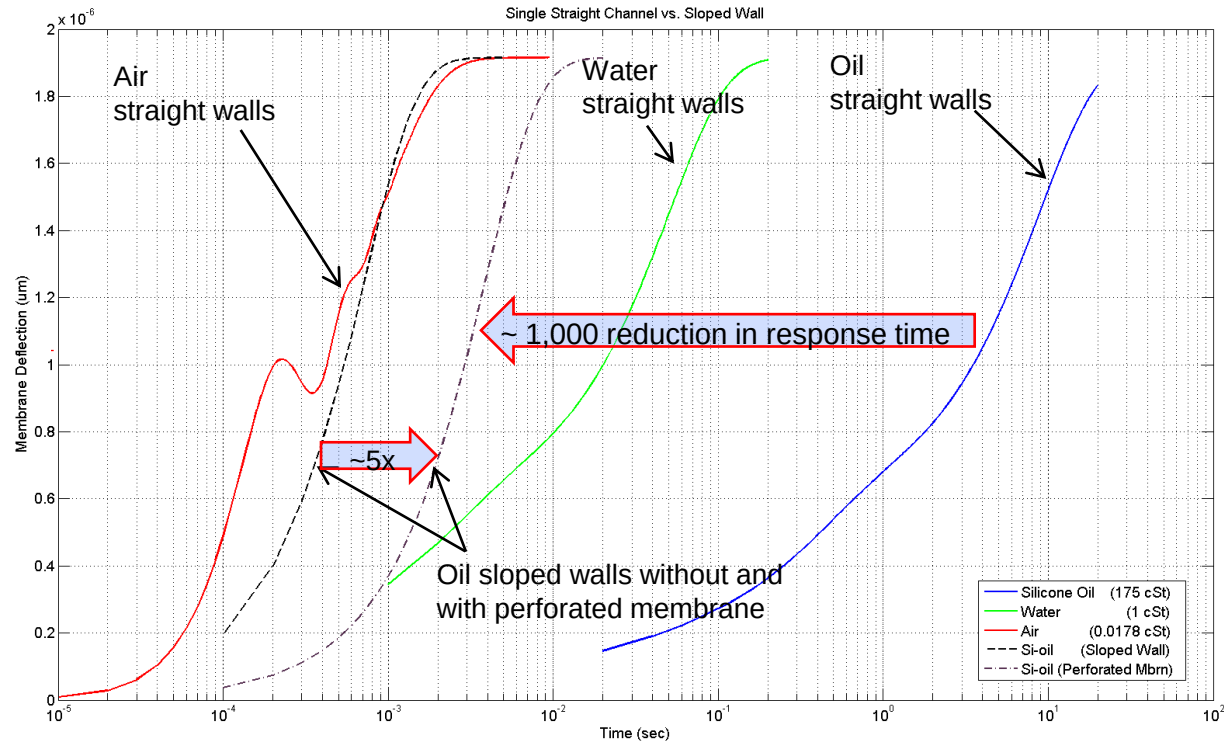
Sloped wall channel



Opening

Perforation structure

Straight vs. Sloped Walls Response time



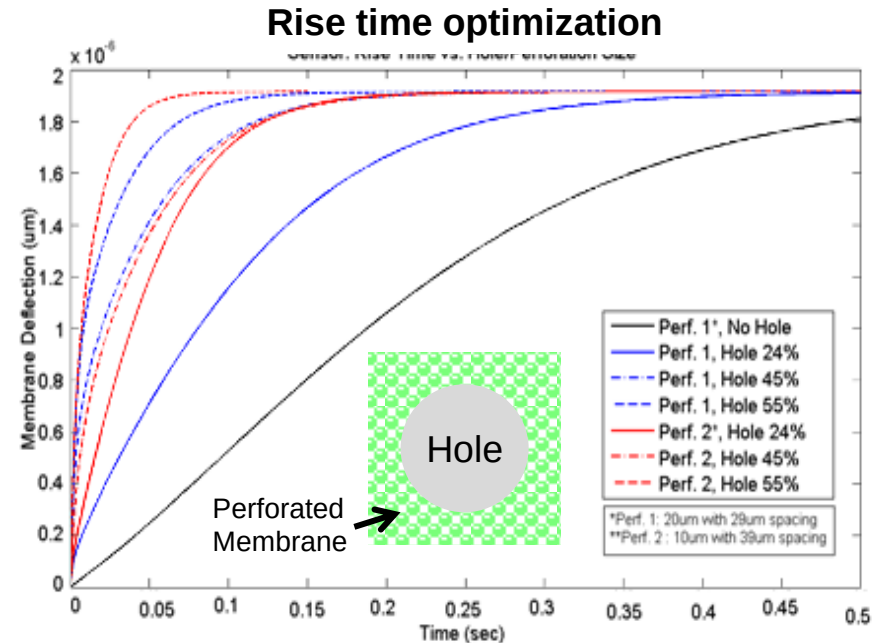
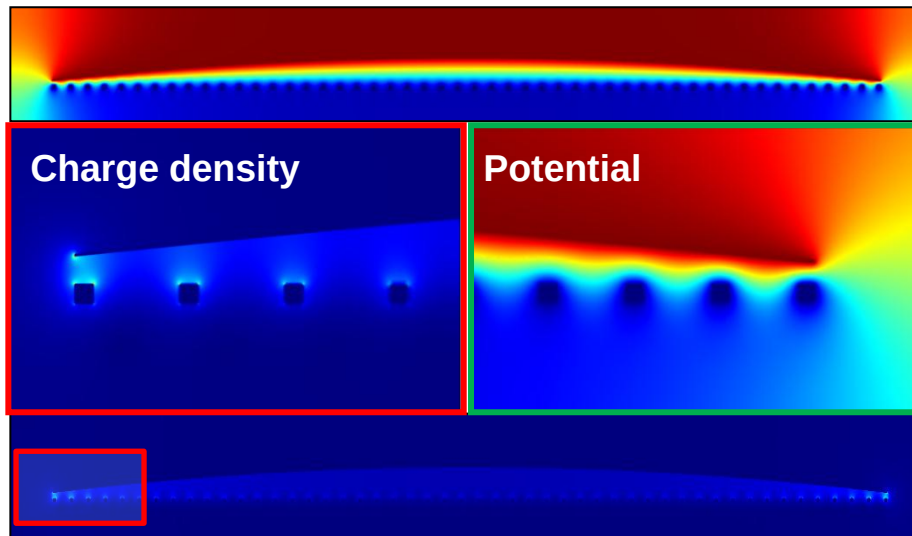
- Could reduce viscosity of fluid, but integration challenges
- Sloped wall design sufficiently reduces response time by $\sim 1,000\times$

FEM to optimize perforated membrane

- Trade off between area (i.e. capacitance and therefore sensitivity) and fluidic resistance (i.e. time response)
- Optimize Parylene thickness for symmetric rise/fall response $\rightarrow 2\mu\text{m}$

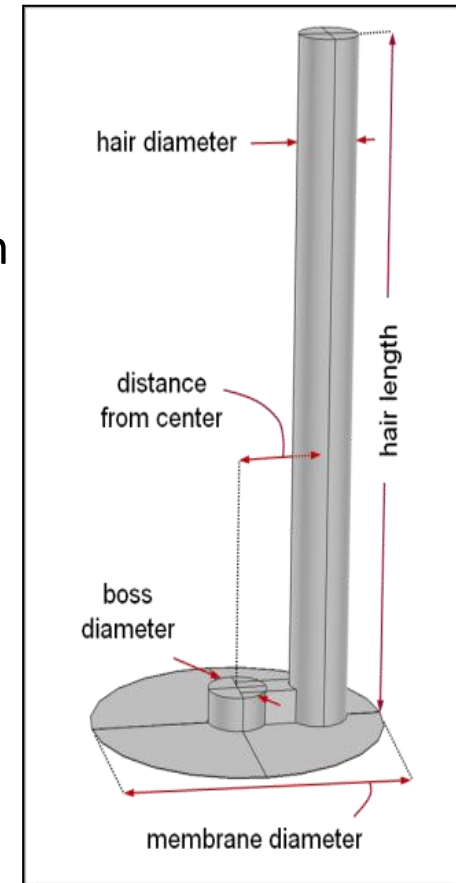
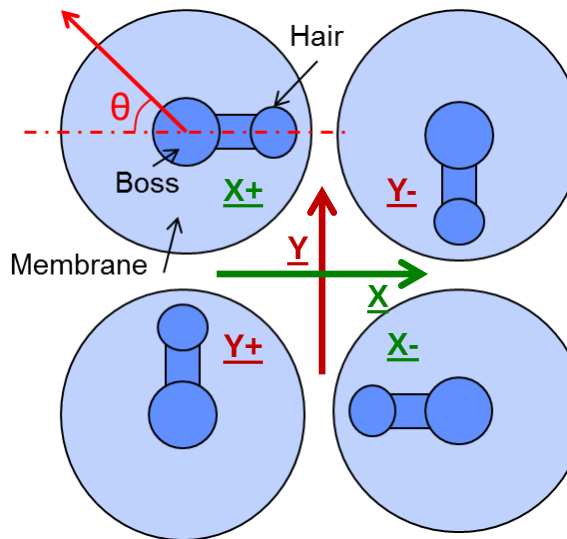
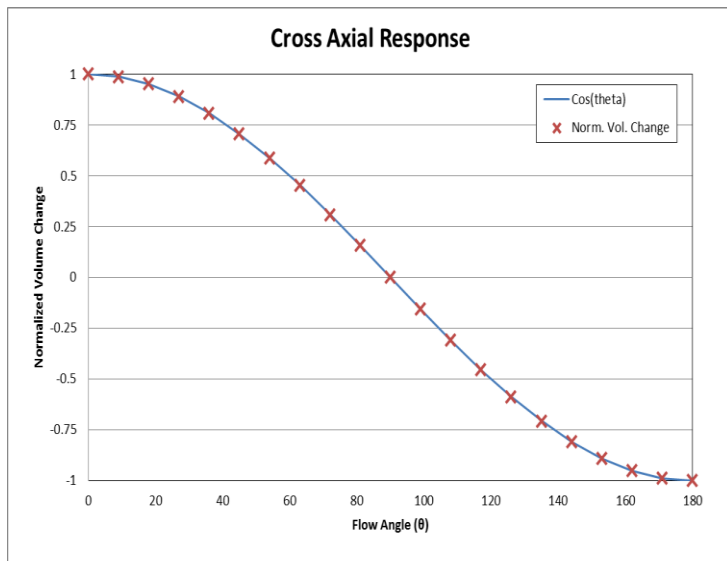
Greatest capacitance contribution comes from edge where gap is narrow $\rightarrow$ put hole in membrane

Using perforations at periphery speeds up fluid flow but only slightly reduces capacitance



Hair placement and sensor array for directionality

- **Optimize hair/boss location**
 - Hair location to maximize membrane deflection → 56% of radius
 - Boss size to maximize deflection → $50\mu\text{m}$
- **Directional Sensing**
 - Four cells / two pairs, each responsible for one direction



2nd Generation Hydraulic Fabrication

New process steps

1) Trench etching



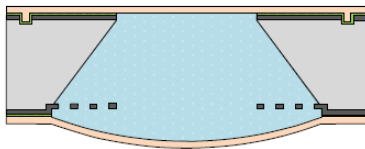
3) DRIE front and back



5) Cytop™ layer



7) Parylene deposition



2) Deep boron doping



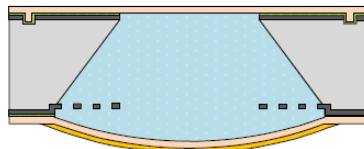
4) Anisotropic Si etching (EDP)



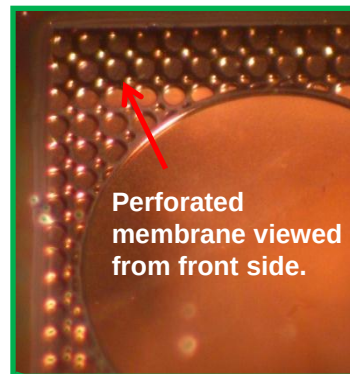
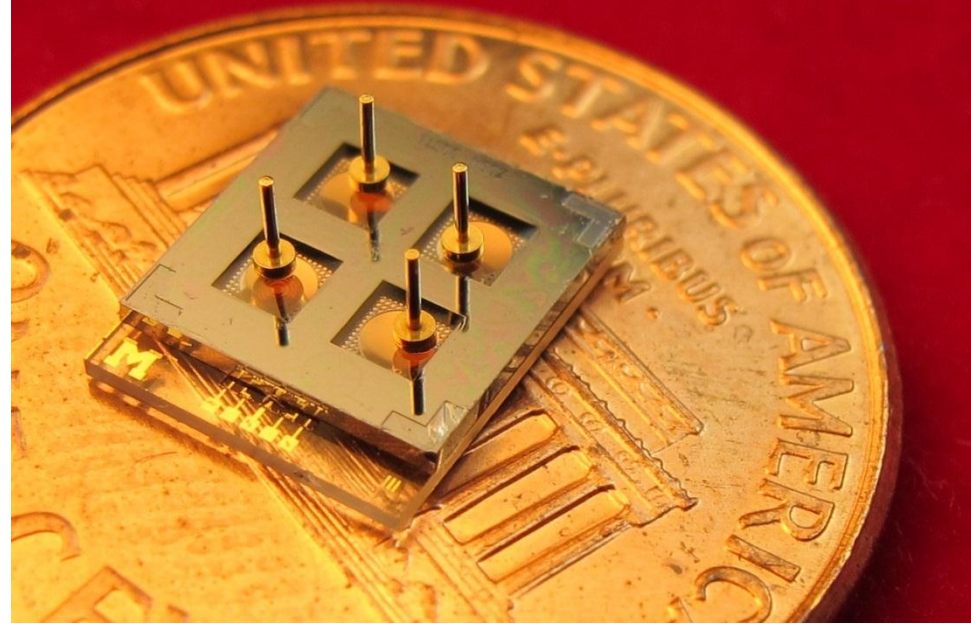
6) Liquid dispensing



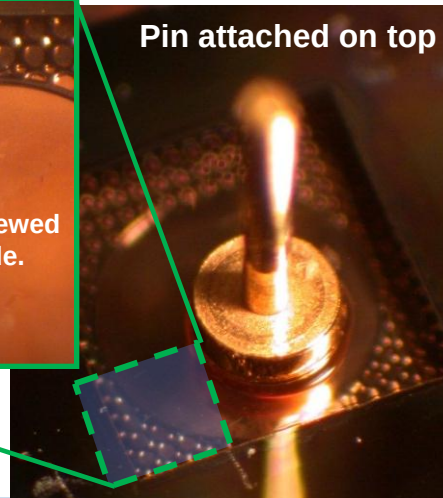
8) Metal deposition (Cr/Au)



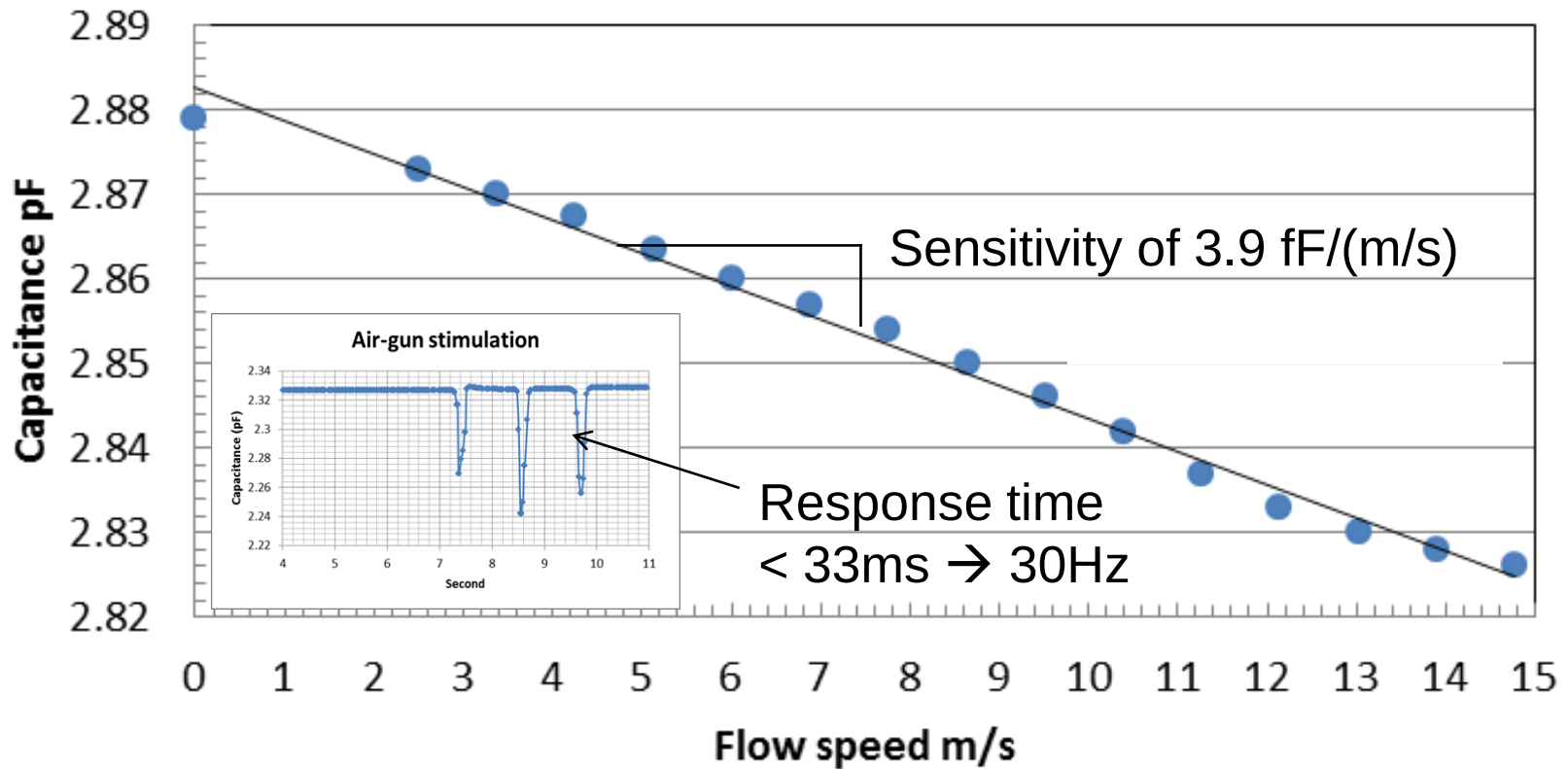
Fabricated and packaged hydraulic sensor



Pin attached on top

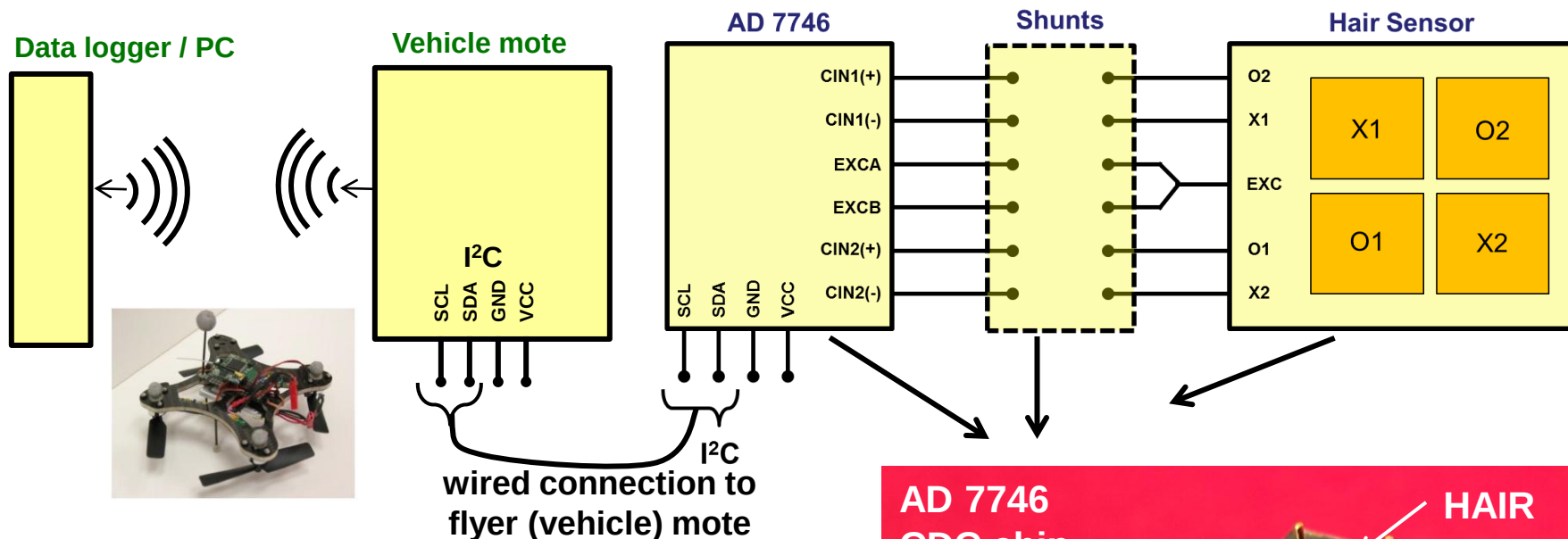


Wind Tunnel and Air gun Tests



- Linear sensor output with sensitivity of 3.9 fF/(m/s) air flow
- **Full scale range: > 15 m/s**
- **Resolution: ~ 2 cm/s**, when in single-ended mode (noise = 80 aF)
- **Response bandwidth ~ 30 Hz**

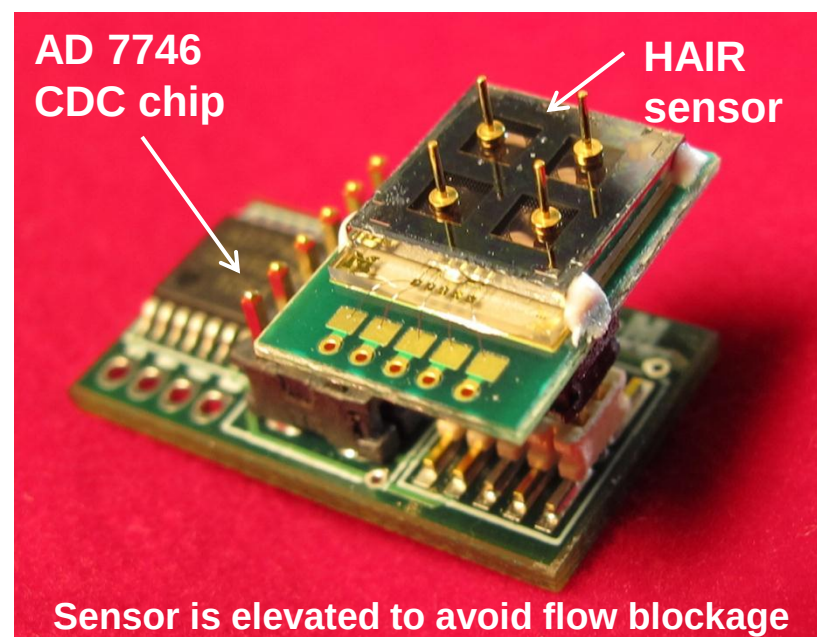
Air Flow Sensor Integration & Performance Summary



Range*	0 – 15 m.s ⁻¹
Sensitivity	3.9 fF/(m/s)
Resolution*	~2.0 cm.s ⁻¹
Response time	~30 ms
Supply	3.3 -5 V
Power	3.5 mW
Weight**	1.2-1.5 g
Output	I ² C

* When read in single ended mode. Resolution in 2 channel mode is ~0.5 m/s, and the range decreases to approx. 2.5-15 m/s.

** 1.2g without header, 1.5g with header

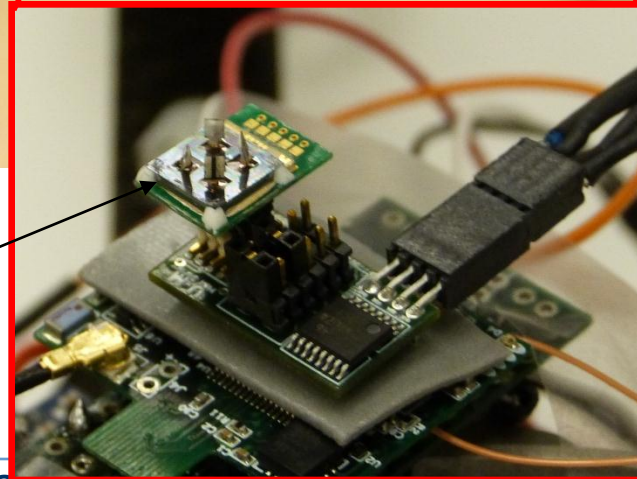
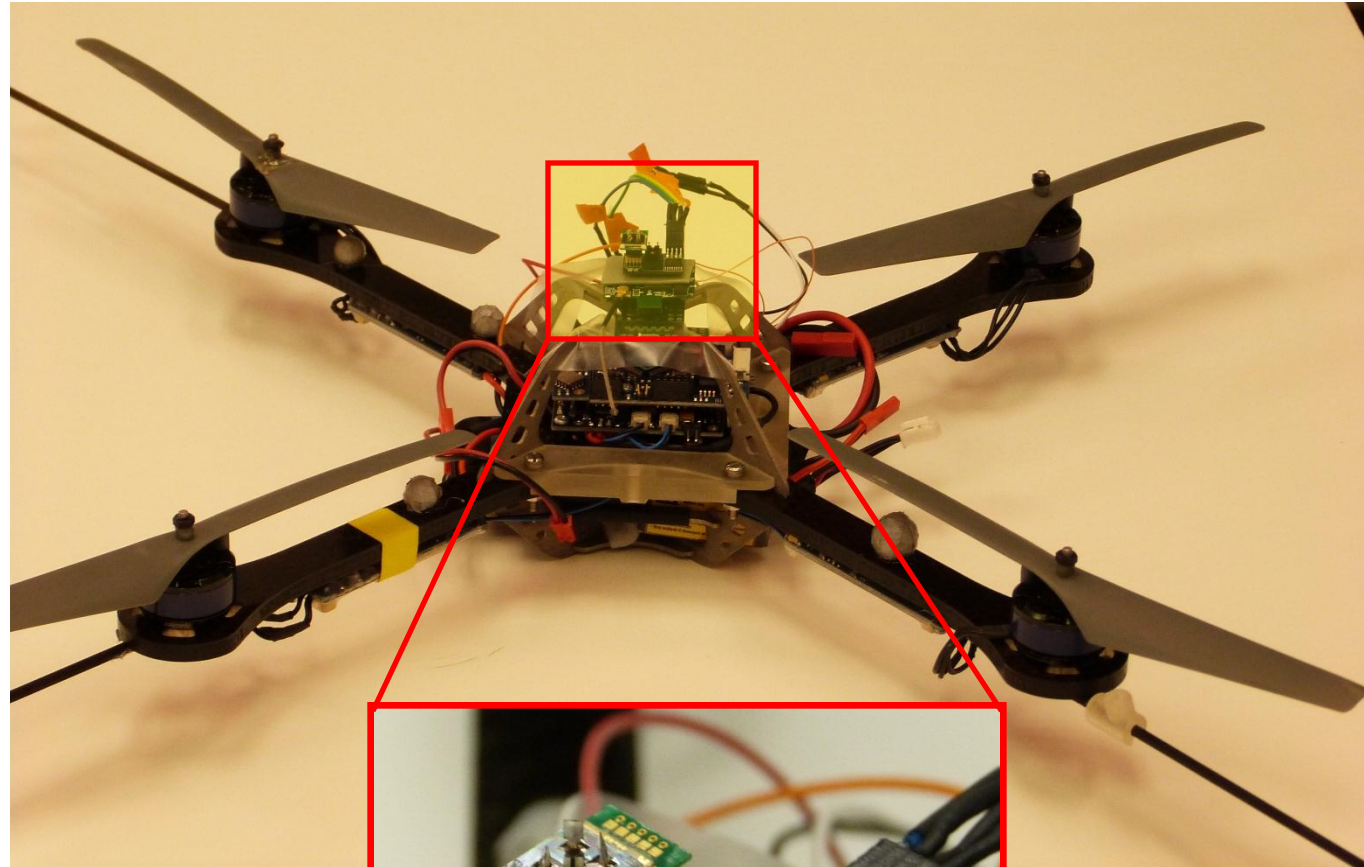


Air Flow Sensor Integration on Flyers

Collaboration with
Prof. Sean Humbert,
UMD

Wind gust detection
with hydraulic HAIR
directional air-flow
sensors:

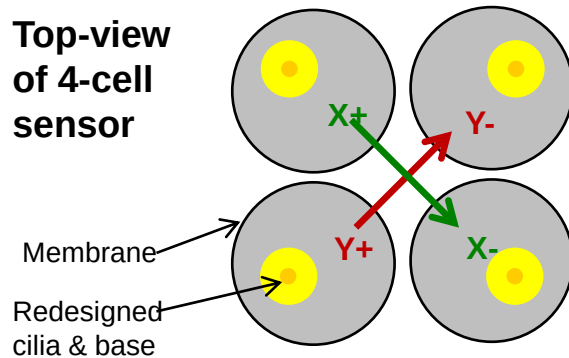
- ✓ Sensor is integrated with flyer mote
- ✓ Data transfer established
- ✓ Closed loop control of vehicle forthcoming



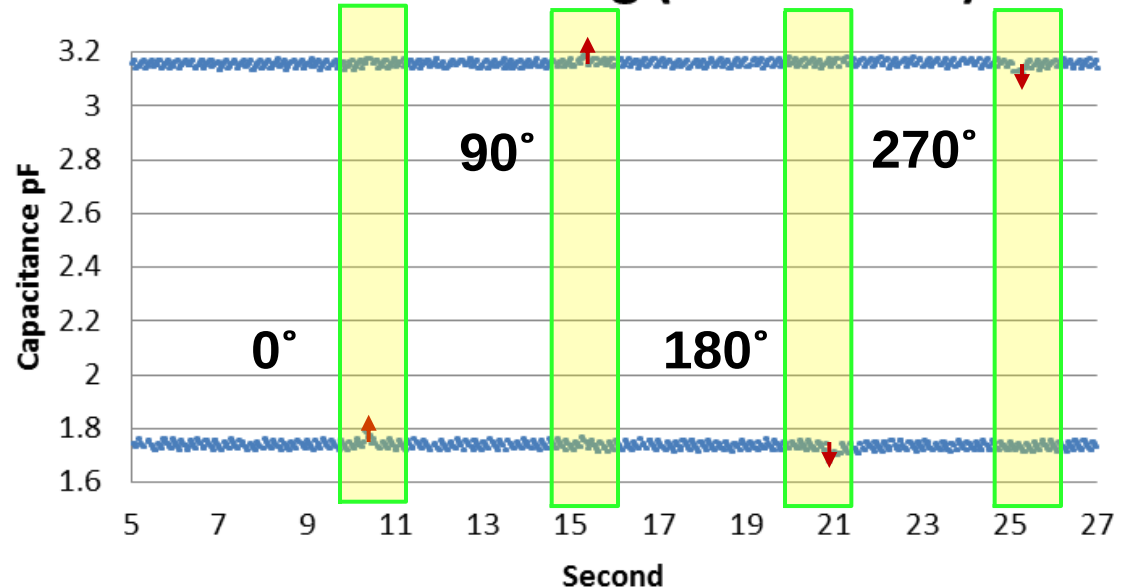
Air flow
sensor
and circuit

Preliminary Results on Directional Sensing

Top-view
of 4-cell
sensor

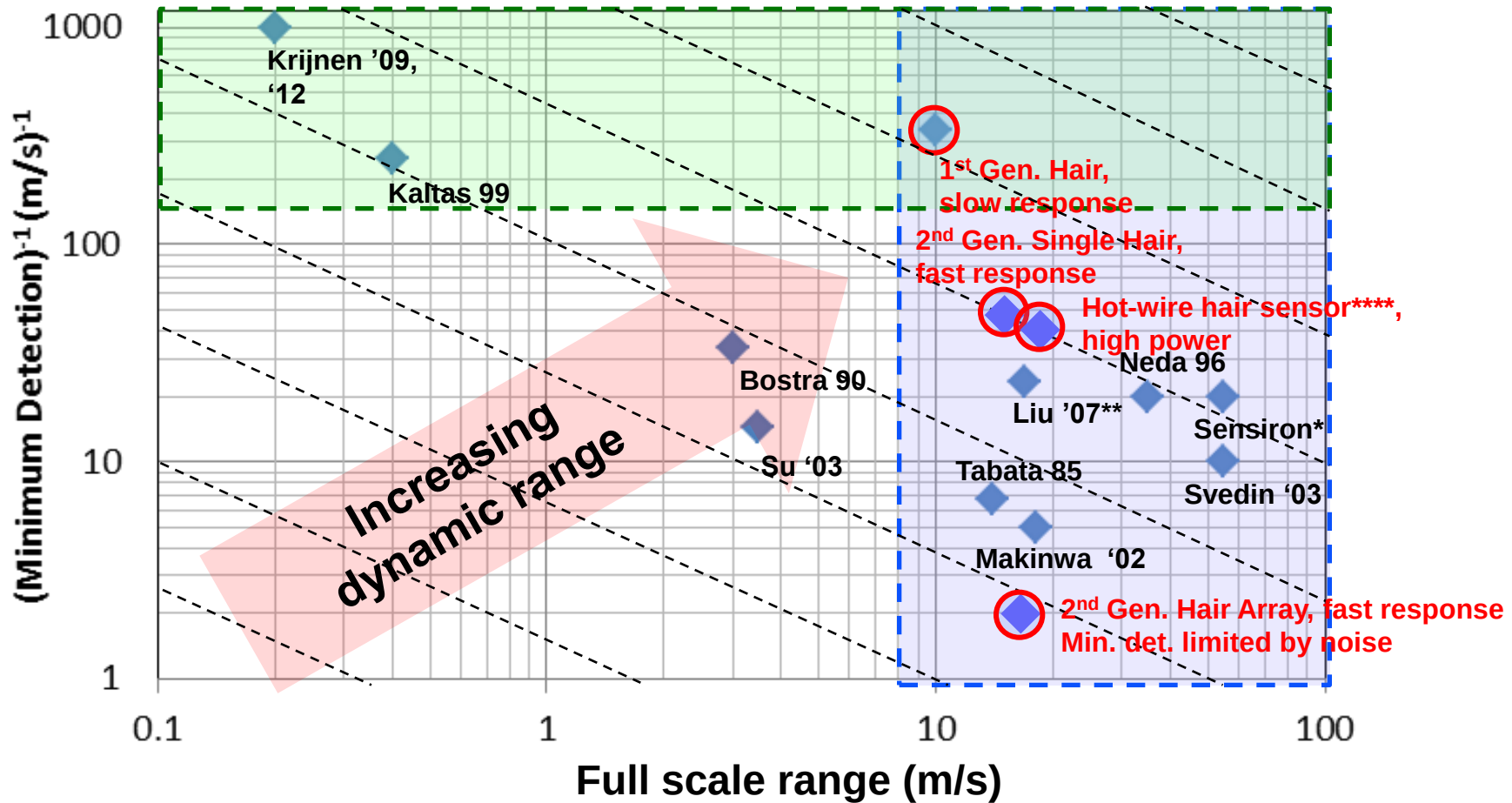


Directional Sensing (Differential)



- For dynamic flight control, need flow directionality
- Redesign cilia + two sensor pairs for in-plane flow vector determination
- Each pair is differentially measured by AD7746 CDC
- Resolution is reduced due to ~100x higher noise level: noise increases from 80aF (single-ended mode) to 10fF (dual channel mode)
- Circuit improvement are ongoing

Trade off between full-scale range and min. detection



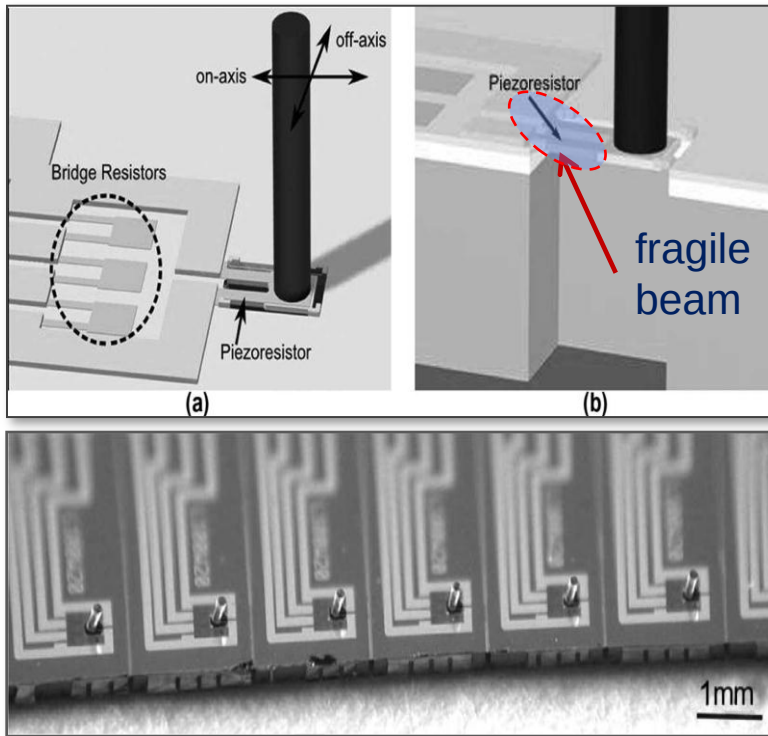
* One of the finest commercially available MFS, Converted data from DS

** The paper states min det. for water flow, not air. 5cm/s is based on our calculation

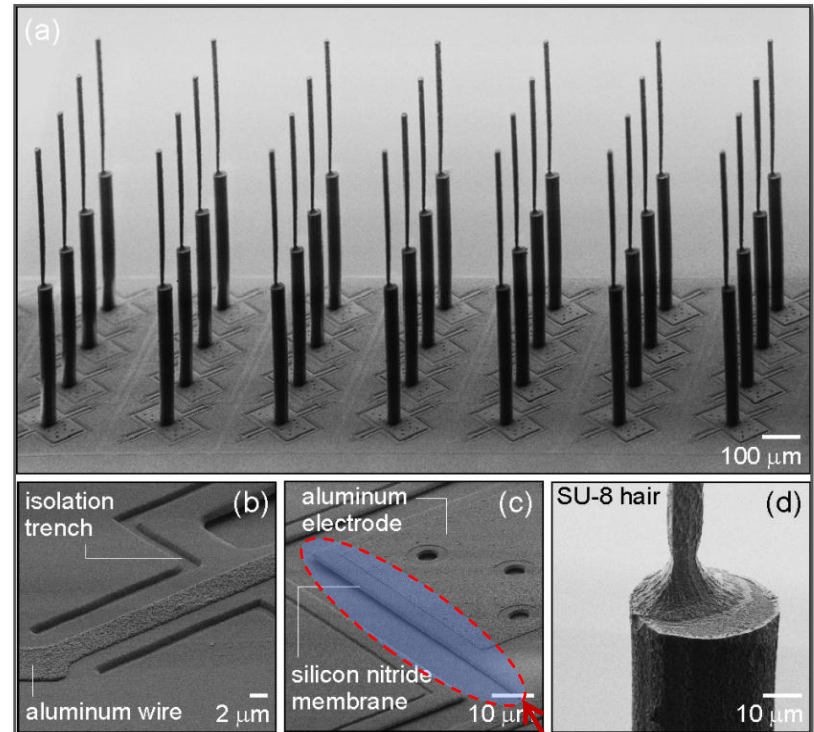
*** Minimum detection limits for data points that are not stated clearly are extracted from measurement graph data points, or assumed to be 0.01 of full-scale range.

**** Published at the Army Science Conference 2010 by Sadeghi, Peterson & Najafi

Alternate Hair-Sensing Schemes



Chang Liu, et al. JMEMS 2007

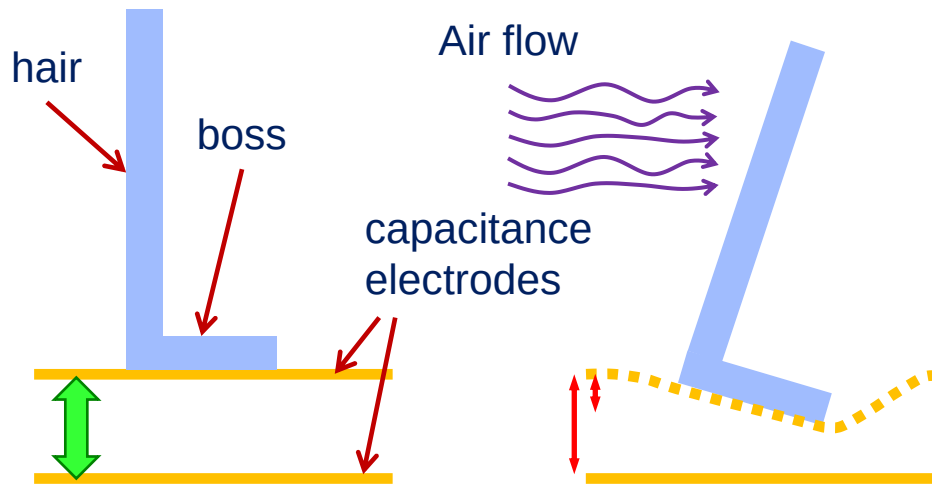


G.J.M. Krijnen, et al. MEMS '09

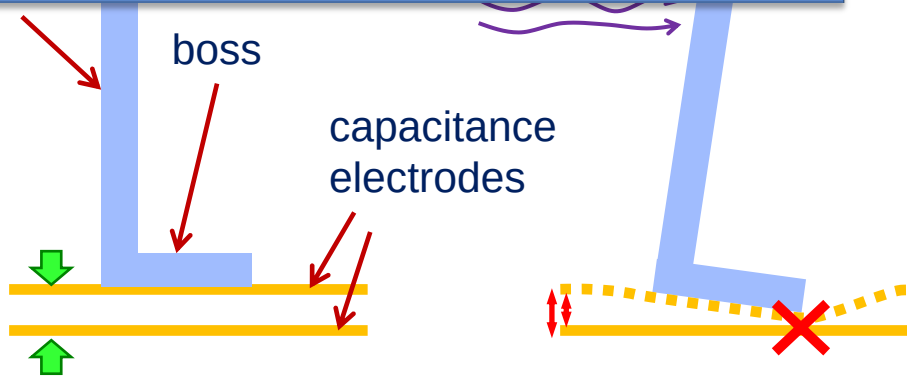
very narrow gap

- Existing approaches: Exposed piezoresistive beam or capacitive gap
- Liquid encapsulation encloses the capacitive gap, offering **robustness and improved dynamic range/resolution**, and **enables new applications** such as sensing in liquid or harsh ambient environments

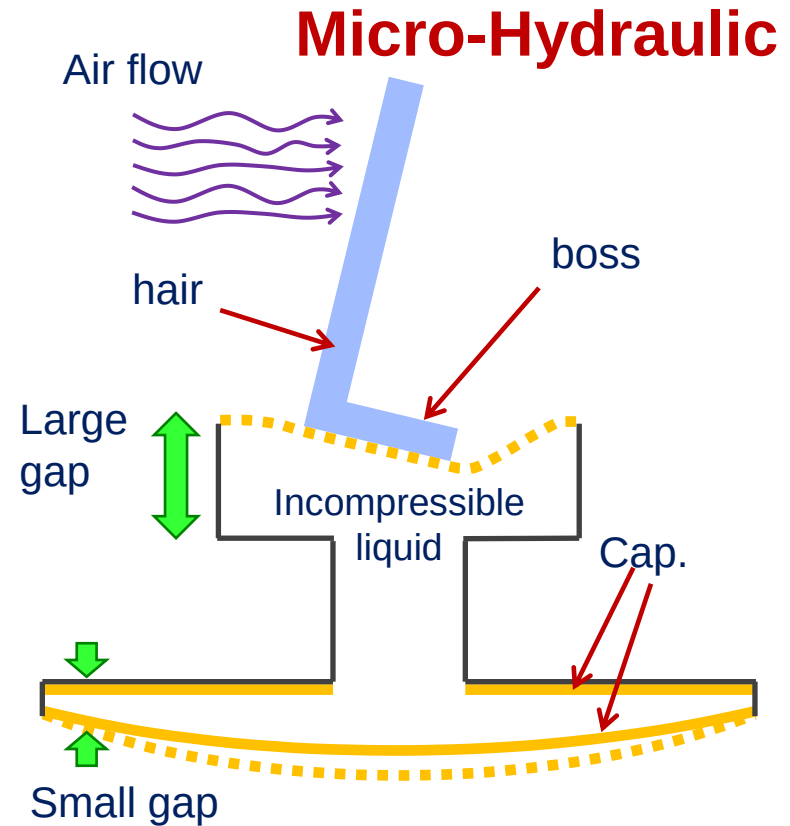
Single Capacitive Flow Sensor vs. Micro-Hydraulic



Single capacitor flow sensors
force trade-off between
sensitivity ↔ full-scale range

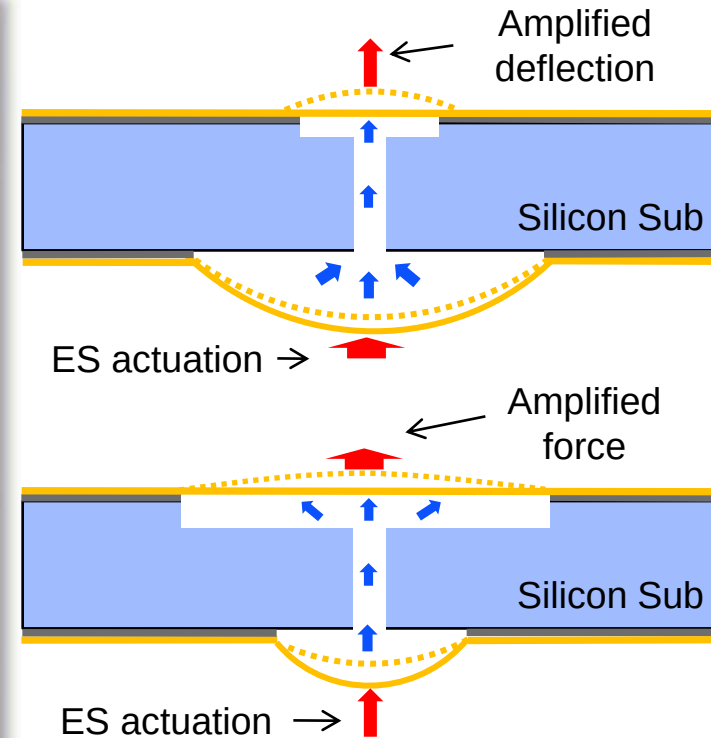
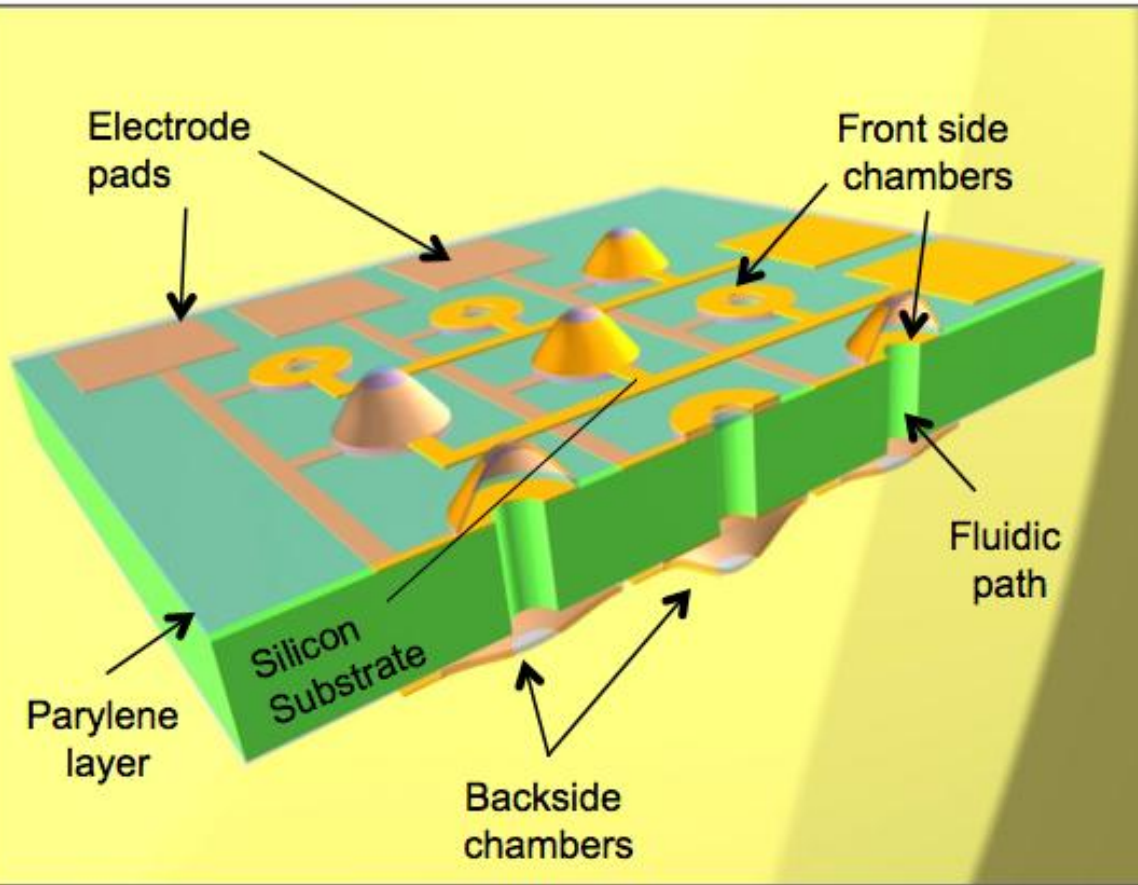


Small single gap



High dynamic range, but
viscous fluid flow reduces
bandwidth

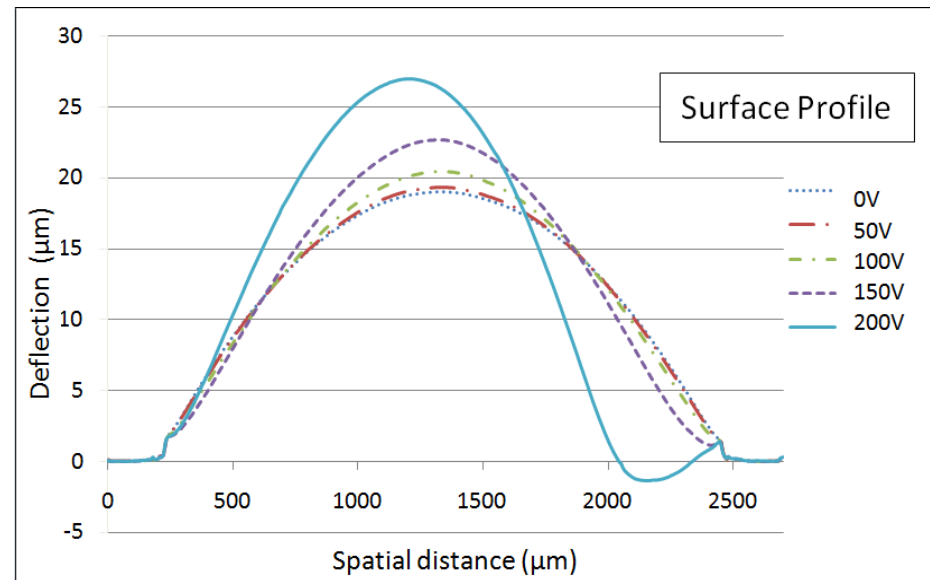
Electrostatic Micro-hydraulic Actuation (EMA)



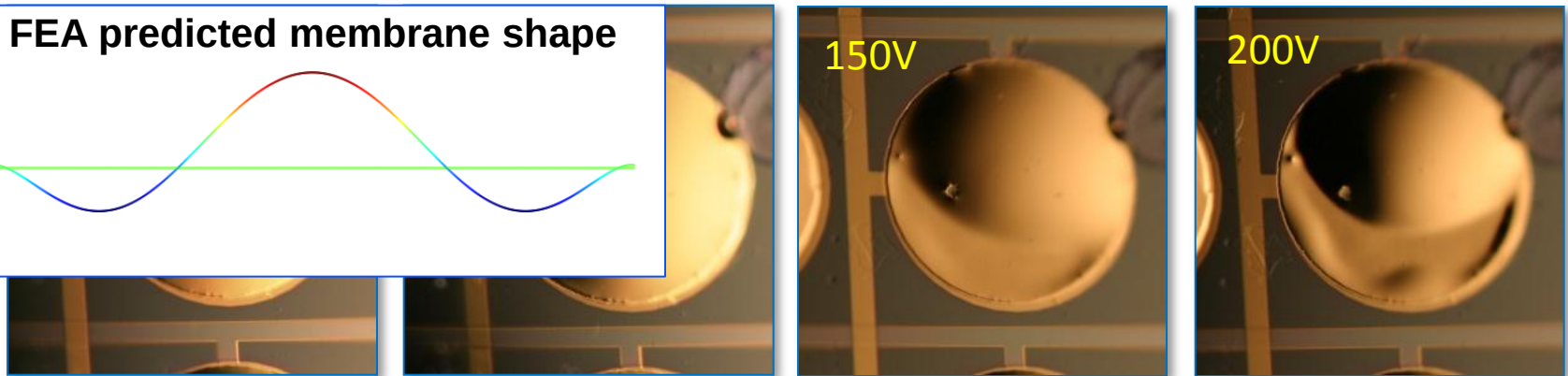
- Integrated electrostatic actuation, wafer-level process
- Array of individually actuated cells; addressability
- Hydraulic amplification for large-force/large-deflection actuation

Experimental Results: Deflection vs. Voltage

- Applied voltage 0-200V
- Bubble height is measured with profilometer; volume change confirmed by LEXT confocal microscopy
- Non-uniform deflection and asymmetric bulging due to edge pull-in



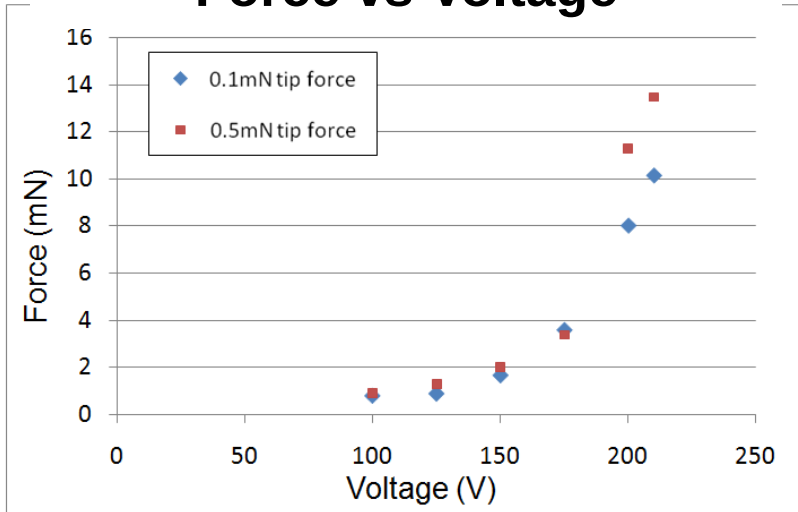
FEA predicted membrane shape



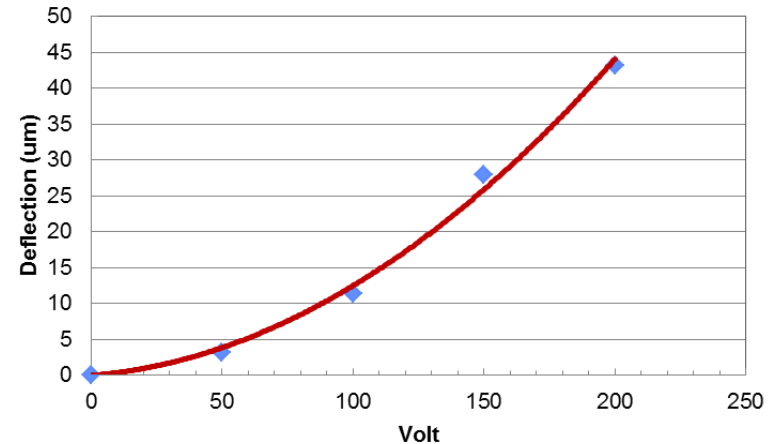
Optical images of one cell with $D=2.2\text{mm}$ at 0, 100, 150 and 200V

Experimental Results: Force, Power, Frequency

Force vs Voltage

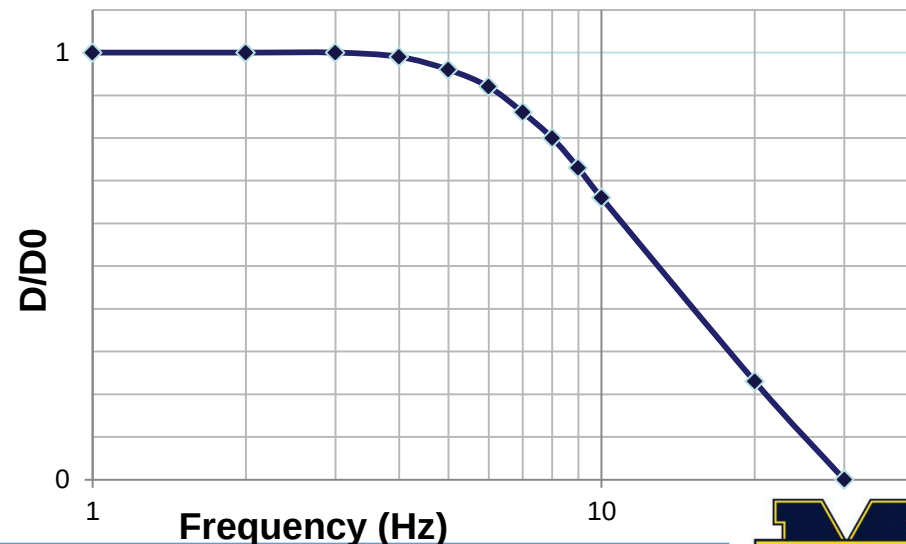


Deflection vs Voltage



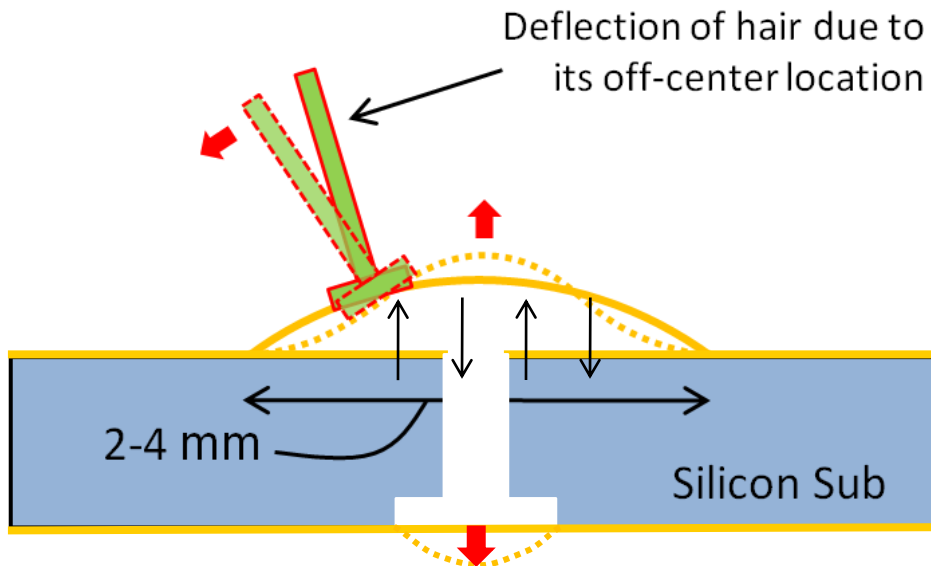
- Force > 12mN
- Deflection > 40 μm
- Power max 24 μW per cell per cycle
- Frequency: DC to 10 Hz (straight wall design)

Deflection vs. Frequency



Actuation for Locomotion

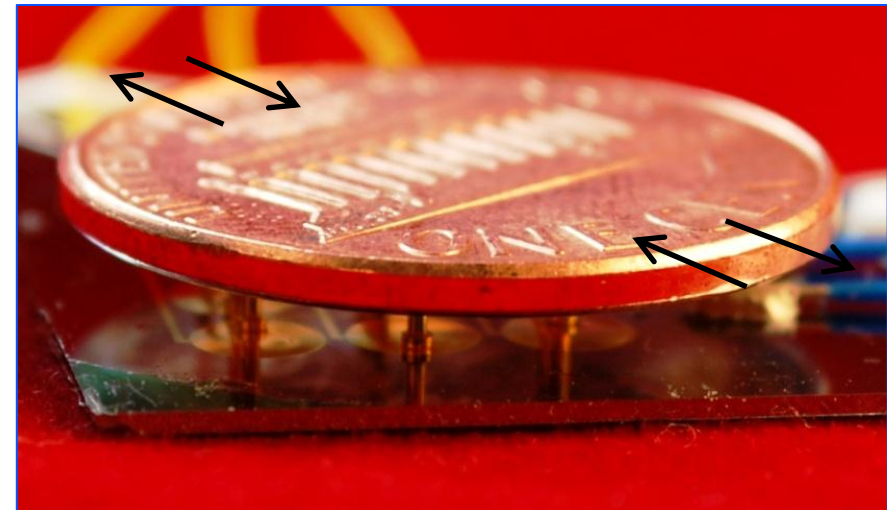
- Phase deflection of multiple membranes creates 'stride'; maximize deflection by off-center positioning of the cilia on membrane
- The device can carry $\sim 5\times$ its own weight, almost 2.5 gram



2 Hz actuation

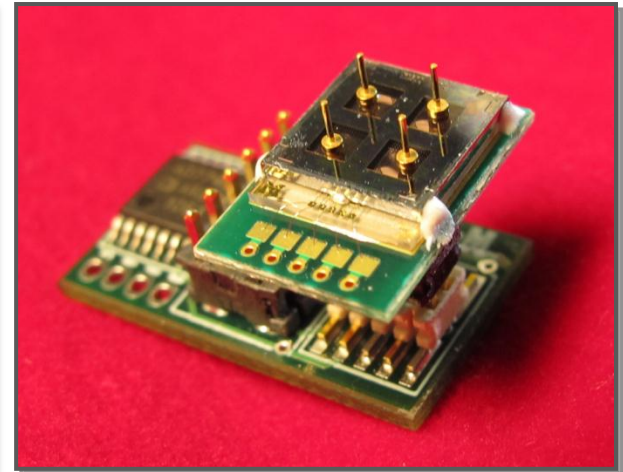
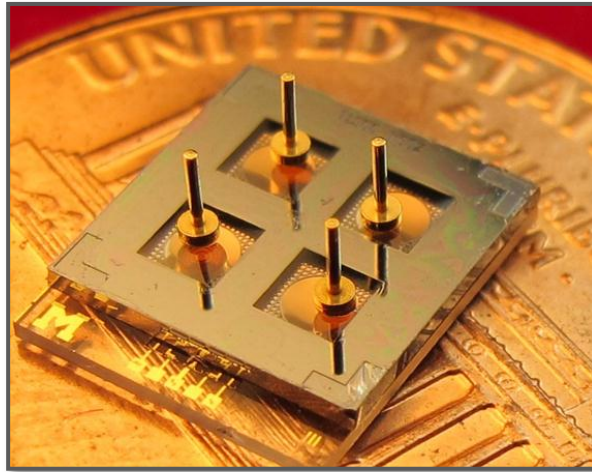


Hairs holding the coin



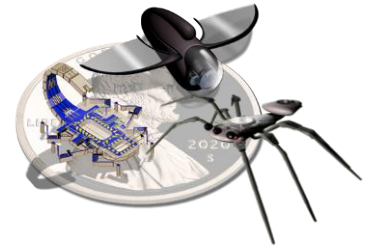
Conclusions

- Novel wafer-level liquid encapsulation for HAIR-like sensing and actuation based on micro-hydraulic, electrostatic architecture
→ new design element in MEMS
- Air flow sensors with record dynamic range and suitable response time for control loop insertion for MAST MAVs (work ongoing)
- High-force/high-deflection micro-hydraulic actuators
- Ongoing and future work on interface circuits, tactile sensing, air foil control, and other hair functionalization



Acknowledgments

- This project is funded by the Micro Autonomous Systems and Technology (MAST) Program of the Army Research Lab under Award Number W911NF-08-2-0004.
- Dr. Will Nothwang, ARL Lead for Microelectronics Center of MAST
- Lurie Nanofabrication Facility, a member of the National Nanotechnology Infrastructure Network, supported in part by NSF
- Undergraduate researchers Bing Zhang and Michael T. Chaney

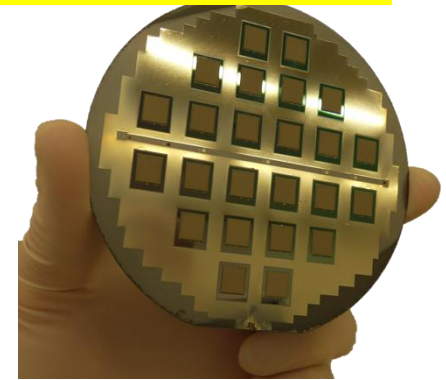
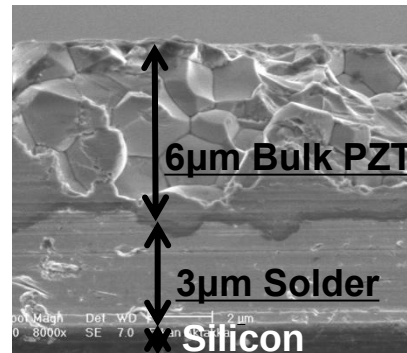


Integration of Bulk Piezoelectric Materials

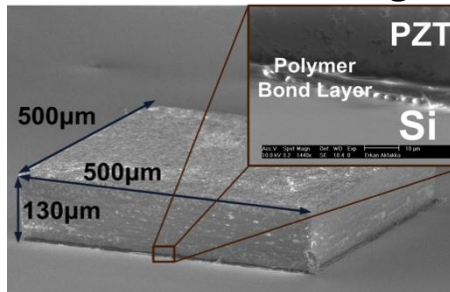
Ethem Erkan Aktakka, Rebecca L. Peterson, Khalil Najafi

Aktakka, et al., Transducers'09, IEDM'10, PowerMEMS'11, HiltonHead'12

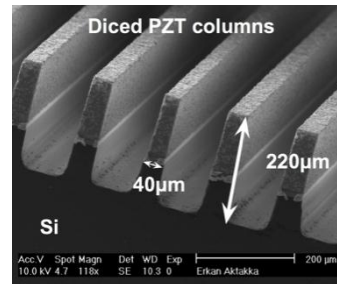
- Characterized bonding & lapping process
- Wide range thickness control (5-100 μ m)
- Wafer-level thickness uniformity ($\pm 0.5\mu$ m)
- Conserved piezoelectricity & polarization
- Post-CMOS compatible process



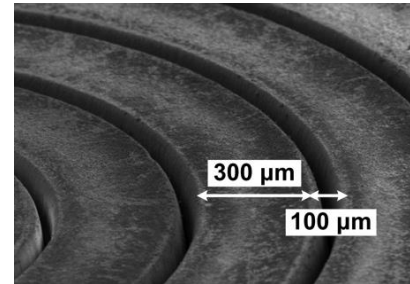
Die-level bonding



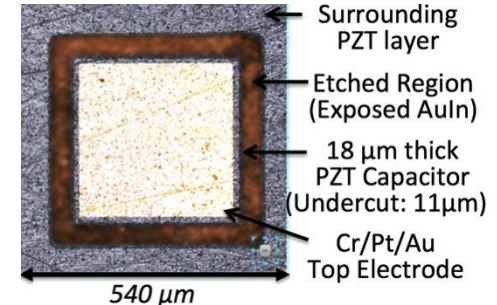
Precision Dicing



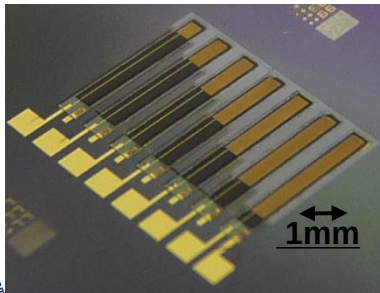
Laser Machining



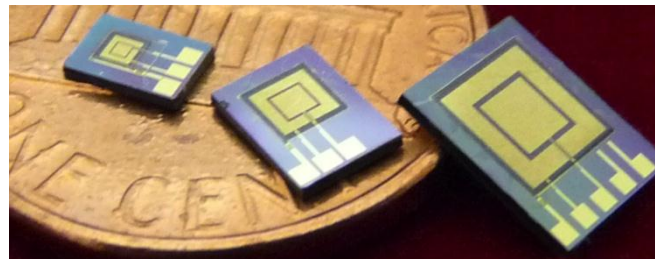
Wet-Etch Patterning



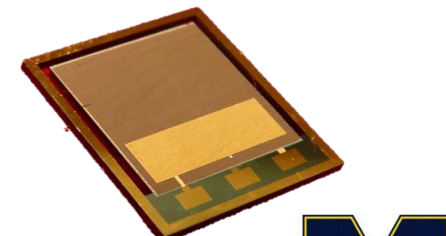
Cantilever Actuators



Diaphragm Actuators



Micro Energy Harvesters



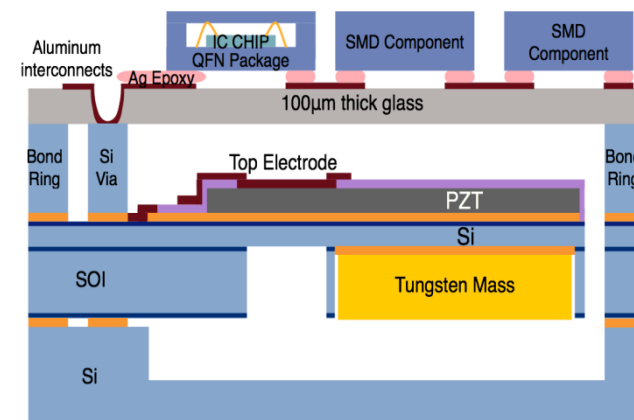
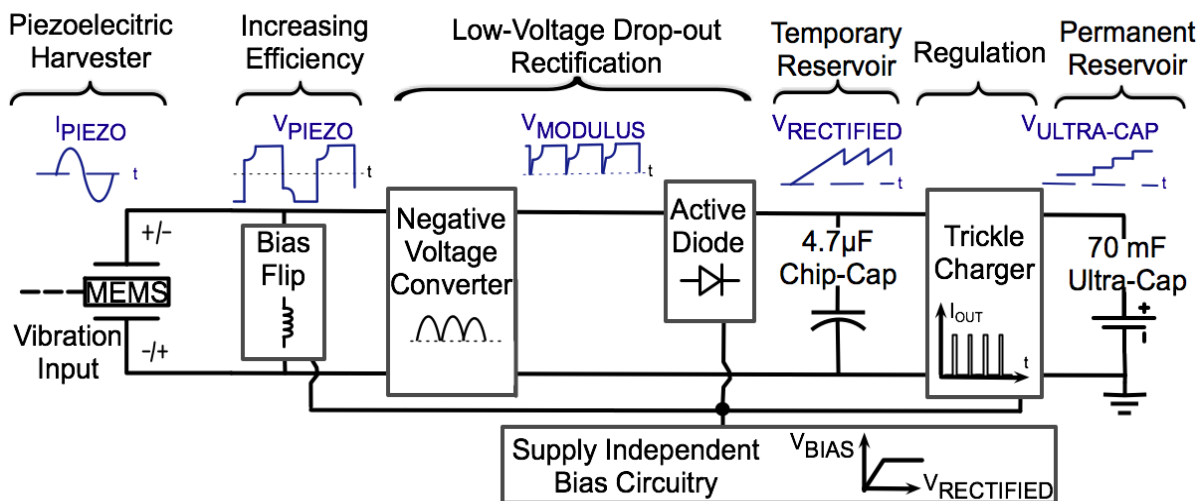
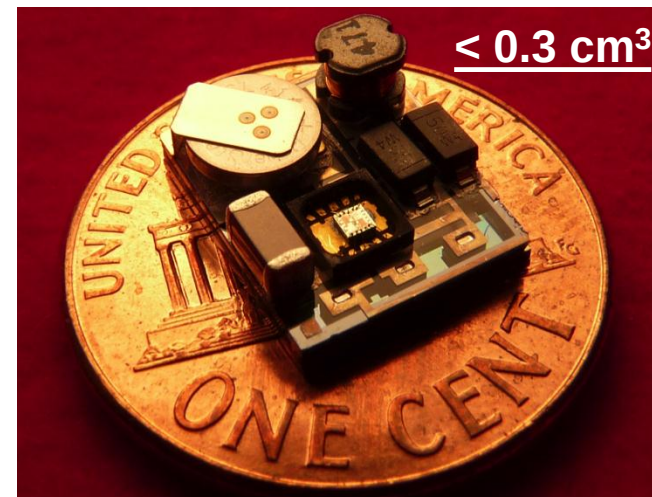
Self-Supplied Inertial Piezoelectric Energy Harvester with Power Management IC

Ethem Erkan Aktakka, Rebecca L. Peterson, Khalil Najafi

Goal: Self-contained vibration energy harvester for industrial applications or vehicle instrumentation

Results:

- High power density (205 μW at 1.5 g vibration)
 - Large bandwidth (14 Hz)
 - Low frequency operation (155 Hz)
- Autonomous charging of an ultra-cap (0 V to 1.85 V)
- No requirement for a pre-charged battery/capacitor



IEDM'10, ISSCC'11, Transducers'11

Funded by DARPA HI-MEMS

A Vibration Harvesting System and Electronics for Bridge Health Monitoring Applications

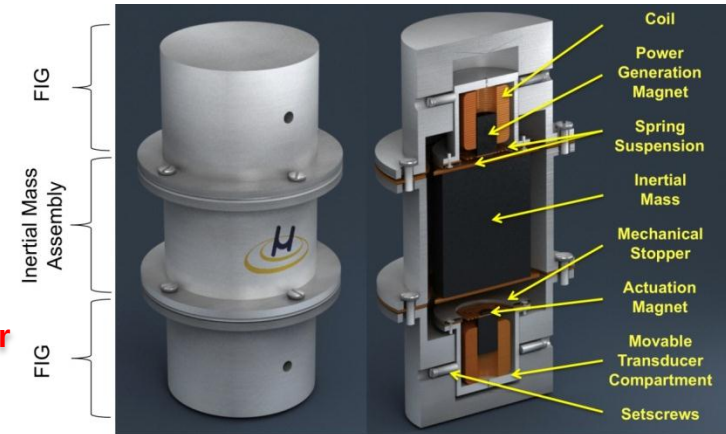
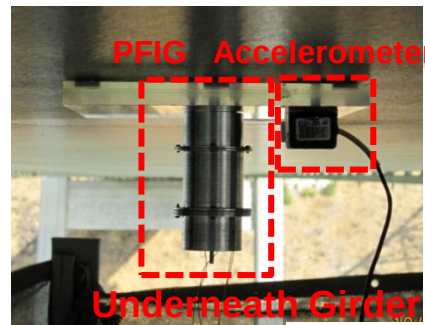
James McCullagh, Tzeno Galchev, R. L. Peterson, and Khalil Najafi

Goal: Harvest low-acceleration, low-frequency, non-periodic vibration energy from bridge to power wireless sensor network for structural health monitoring

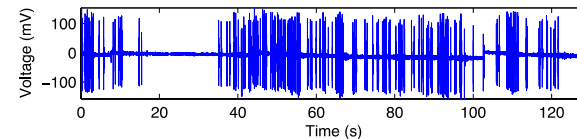
Results:

- 5th Generation **Parametric Frequency Increased Generator (PFIG)** built
- Achieved record low threshold acceleration of 35mg ($1g = 9.8m/s^2$)
- Increased avg. power to 131 μW at 11 Hz
- Testing PFIG + circuit on bridge to generate DC output voltage

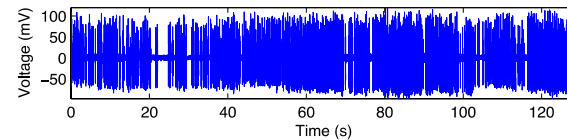
Galchev, et al., J. Micromech. Microeng. 21, 1, 2011; Two papers at Transducers 2011; PowerMEMS 2010



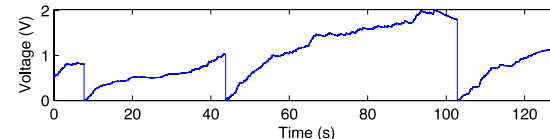
PFIG architecture and installation on suspension bridge



PFIG output voltage 1



PFIG output voltage 2



Storage Capacitor, (discharged manually)



HAIR Based Sensing and Actuation

Mahdi M. Sadeghi, Becky (R. L.) Peterson, and Khalil Najafi

*Electrical Engineering and Computer Science (EECS) Dept.
University of Michigan*

The 2nd Multifunctional Materials for Defense Workshop
August 1, 2012
Arlington, VA